



**COVALENT
METROLOGY**

Welcome

PHOTO-INDUCED FORCE MICROSCOPY (PIFM): AUGMENTING SURFACE ANALYSIS WITH AFM CHEMICAL MAPPING

Sung Park, PhD

Cofounder and CEO,
Molecular Vista

Graceson Aufderheide

Applications Engineer,
Molecular Vista

July 27, 2023 | 11am PT



COVALENT
ACADEMY

Industrial Applications of
Advanced Metrology

Episode 35



Silicon Valley-based analytical labs and platform delivering quality data and expert analysis for advanced materials and device innovation



Comprehensive Solutions Stack

70+ cutting-edge instruments, offering 100+ techniques

Analytical Services

Advanced Modeling

Method Development

Enterprise Metrology Solutions



Affordable and Fast

Fast Turnaround Times

Volume Savings

Instant Access to Data and Reports in Secure Portal



Flexible Business Model

Custom Consulting Solutions and Certified On-site Support

Training and Certification on Instrumentation

Co-op and Tool-Share Opportunities

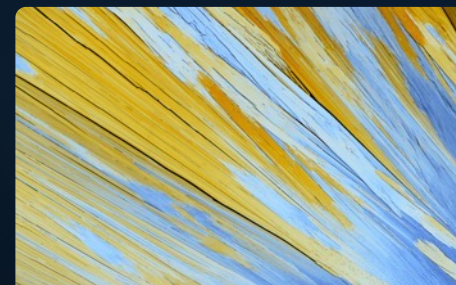
Laboratory Audits



Rich Network of Partnerships

Partner to the World's Leading Instrument Manufacturers and Labs

Expanding Instrumentation, Lab Connections, and Learning



Who We Are, Who We Serve

500+ Clients, 40 – 60 Added / Quarter

60+ Employees, 25% + hold PhDs

Cutting-edge Analytical Capabilities

Silicon Valley Lab based in Sunnyvale, CA

PCBA, Semiconductor, and Electronic Device Metrology & Failure Analysis

- DPA / Mechanical Cross-section
- Dye & Pry Test
- EBIC / OBIC failure analysis
- Hot Spot Detection
- IR Imaging / Emission Microscopy
- NIR Imaging
- Root-Cause Failure Analysis

Electron Microscopy and Scanning Probe Microscopy

- AFM & Advanced AFM Modes (EFM, KPFM, MFM, PFM)
- Scanning Acoustic Microscopy (SAM)
- SEM (+ EDS)
- FIB-SEM (+ EDS)
- S/TEM (+ EDS / + EELS)
- Nano-indent / Nano-scratch

Optical Microscopy & Spectroscopy

- Chromatic Aberration
- Digital Optical Microscopy
- FTIR and ATR-FTIR
- Laser Scanning Confocal Microscopy
- Spectral Ellipsometry
- UV-Vis-NIR Spectroscopy
- White Light Interferometry

X-Ray Characterization

- X-Ray Diffraction (XRD)
- X-Ray Reflectometry (XRR)
- Micron-spot ED-XRF
- WDXRF
- Micro-computed X-ray Tomography (Micro-CT)
- 2D X-ray Inspection & X-ray Radiography

Elemental / Chemical Composition Analysis

- EPMA
- GD-OES
- GC-MS
- ICP-MS and LA-ICP-MS
- Raman Microscopy & Spectroscopy
- NMR (1D or 2D; solid / liquid)

Particle Analysis

- Dynamic Light Scattering (DLS)
- Laser Diffraction Particle Size Analysis (PSA)
- **Particle Zeta Potential**

Material Property Characterization

- DSC
- DMA & TMA
- Rheometry
- TGA
- **Solid Surface Zeta Potential**
- Porometry / Porosity
- Gas Adsorption
- Gas Pycnometry
- Foam Density
- Tap Density

Surface Spectroscopy Analysis

- Dynamic-SIMS
- ToF-SIMS (Static-SIMS)
- Ion Scattering Spectroscopy (ISS)
- Ultraviolet Photoelectron Spectroscopy (UPS)
- X-ray Photoelectron Spectroscopy (XPS)

Today's webinar is in partnership with



- Team of Experts behind:
 - **Photo-Induced Force Microscopy (PiFM)**
 - **Photo-Induced Force IR Spectroscopy (PiFIR)**
- Techniques **enable mapping and analyzing the chemistry of smaller volumes than ever before.**
- Collaboration with Covalent brings these solutions to new applications and supports advanced device & materials research.

Other Covalent Partners



Toray Research Center, Inc.

Dr. Sung Park

*Co-founder and CEO,
Molecular Vista*



- Received a PhD in Applied Physics from Stanford University in 1986.
- After graduating, he worked for almost 2 decades **developing new scientific instrumentation** specializing in **advanced technologies for atomic force microscopy**.
- In **2012**, he **co-founded Molecular Vista** to empower analysts to **probe and understand matter at the molecular level** through **quantitative visualization**.





molecular
V I S T A

Infrared Photo-induced Force Microscopy

July 27, 2023
Sung Park
sung@molecularvista.com

Complements other Nanoscale Analytical Techniques

	IR PiFM	Raman	FTIR	TOF-SIMS	XPS	TXRF	SEM/EDS	TEM	Auger
Species Detected		M.I.	M.I.	M.I.	M.I.	E.I.	E.I.	E.I.	E.I.
Chemical Mapping		Yes	Yes	Yes	Yes	Yes (Elemental)	Yes (Elemental)	Yes (Elemental)	Yes
Lateral Resolution		> 0.5 μm	> 10 μm	> 0.2 μm	10 μm – 2 mm	~ 1 mm	1 nm* 0.5 μm EDS	0.2 nm* 1 ~ 20 nm EDS	~ 10 nm
Depth Probed		> 500 nm	1 μm	1 nm	10 nm	10 nm	1 μm	~ 100 nm	10 nm

* Imaging

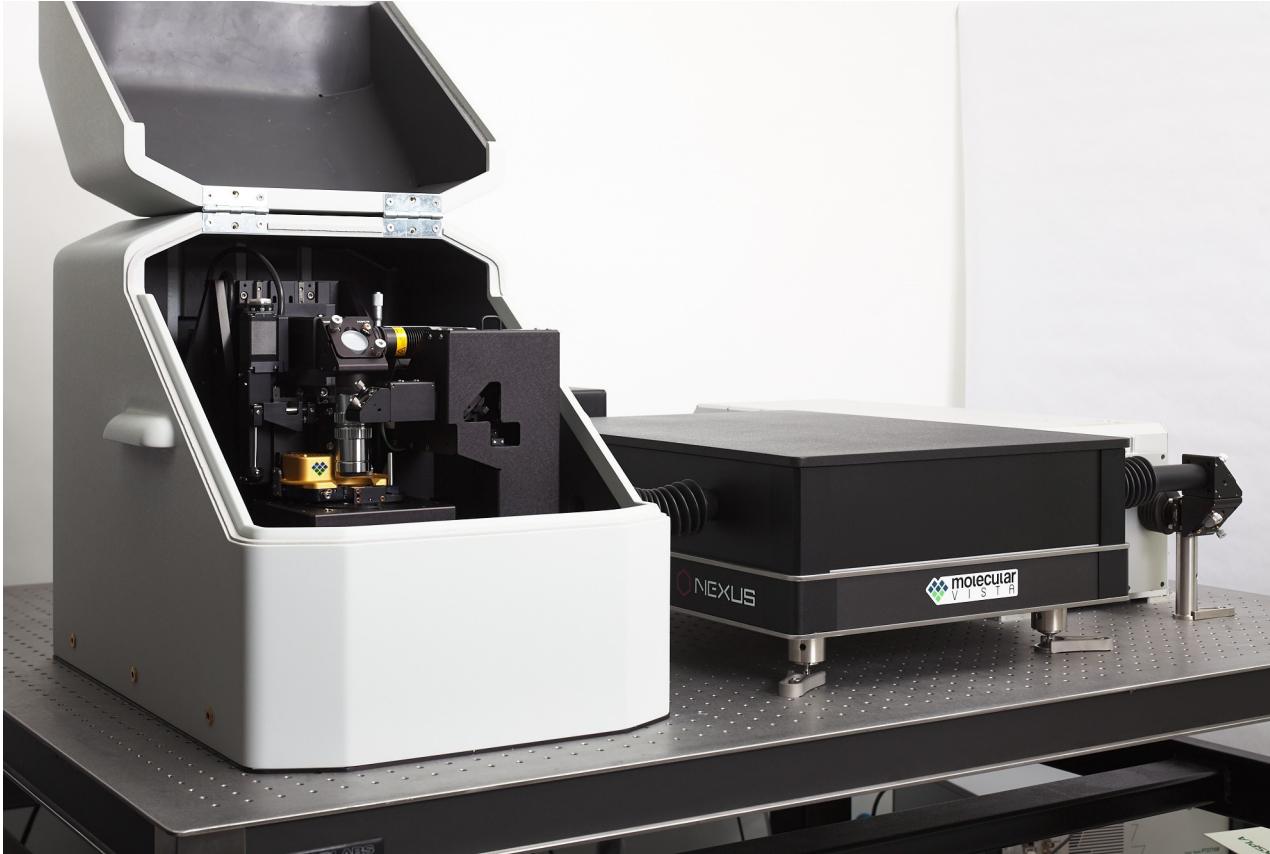
M.I. Molecular information

E.I. Elemental information

IR PiFM brings molecular analysis to the realm of true nanoscale, providing both IR absorption spectra and chemical mapping with ~ 5 nm spatial resolution and monolayer sensitivity.



IR PiFM on Vista AFM Platform



Vista 75

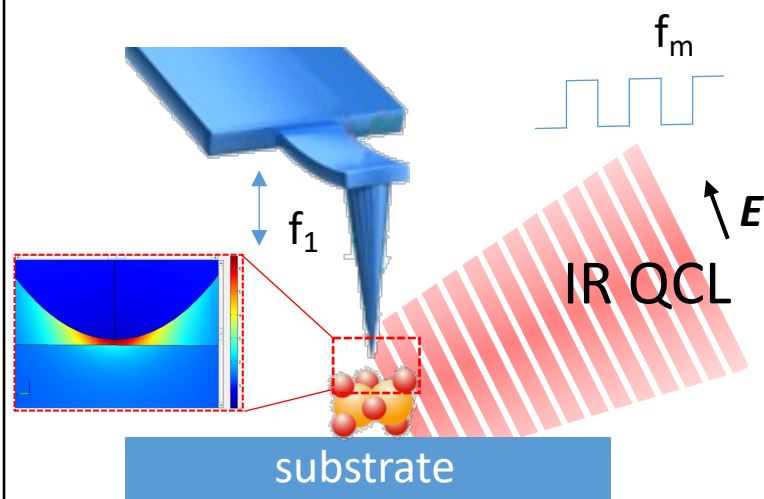
- Sample Size: 4" diameter x 1" height
- Scan Range: 80 x 80 x 12 μm^3
- AFM + multiple laser sources
- IR PiFM + other optional near-field techniques
- If a sample can be analyzed via AFM, IR PiFM is possible
- Vista One and Vista 200 also available



Infrared Photo-induced force microscope (IR PiFM)

(a)

Bi-modal Non-contact
AFM



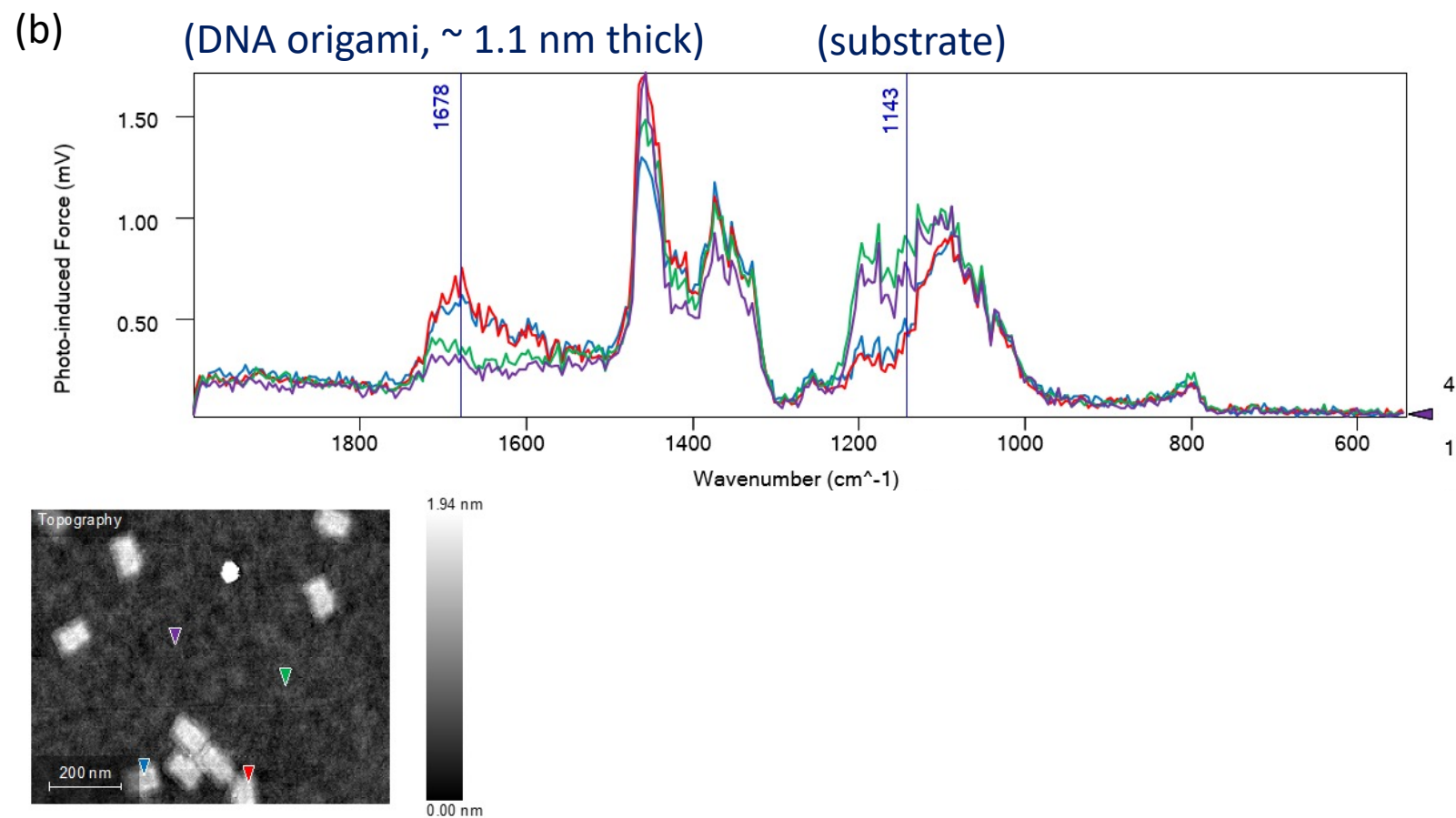
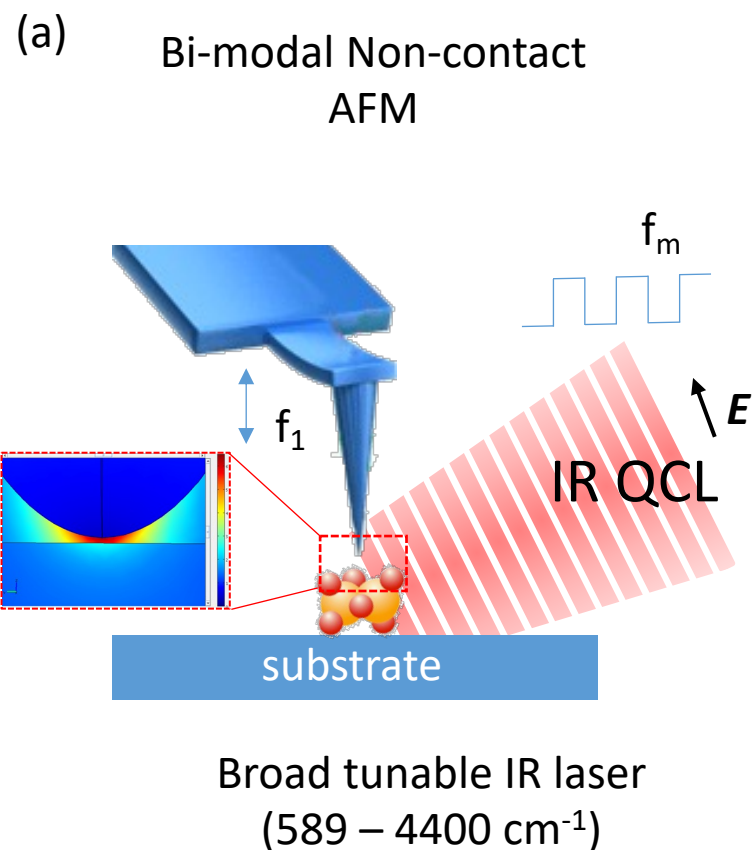
Broad tunable IR laser
(589 – 4400 cm^{-1})

Norway spruce fiber wall



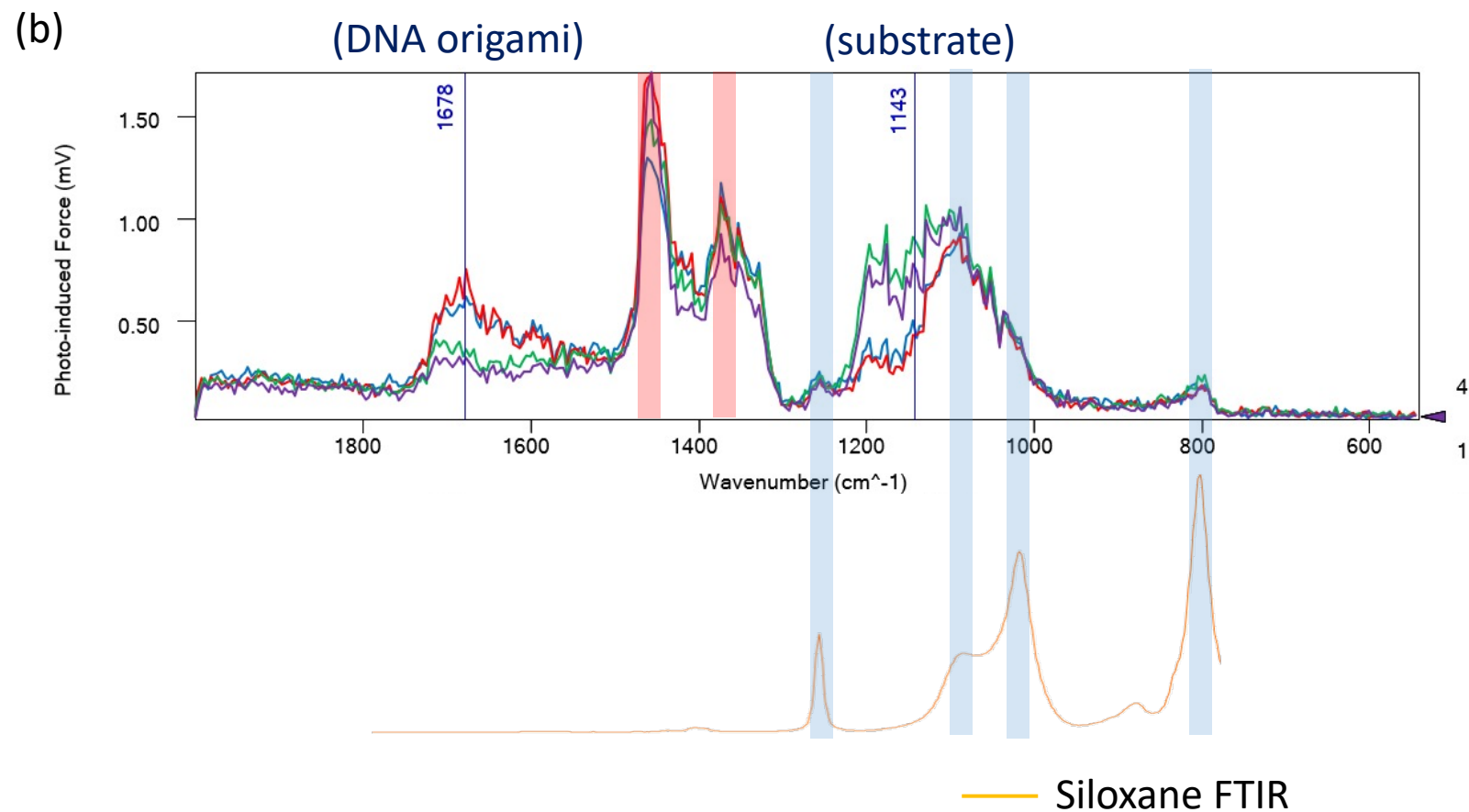
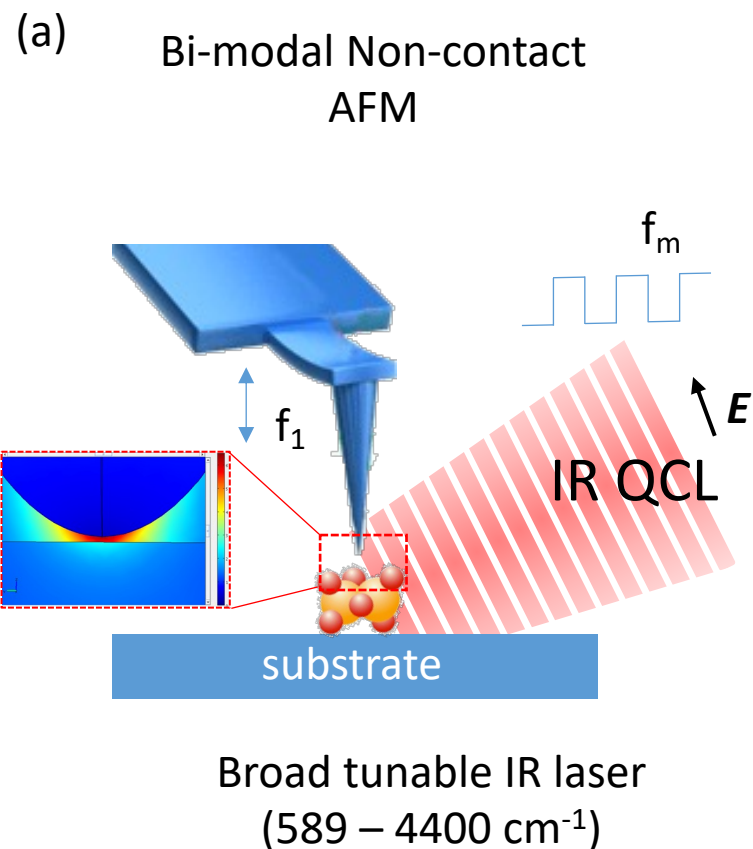
Infrared Photo-induced force microscope (IR PiFM)

Monolayer Sensitivity



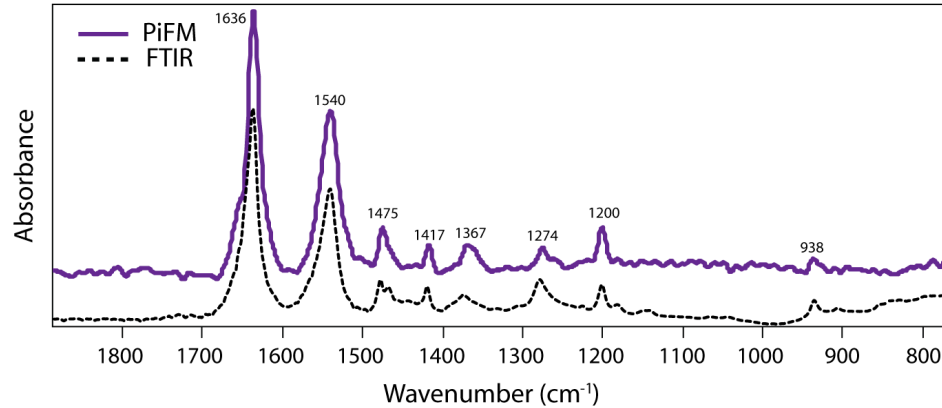
Infrared Photo-induced force microscope (IR PiFM)

Monolayer Sensitivity

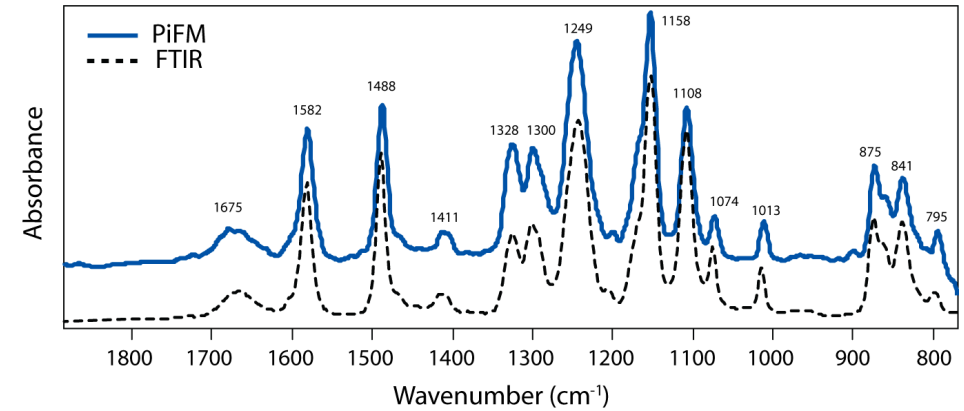


Excellent Agreement between Nanoscale PiF-IR and FTIR Spectra

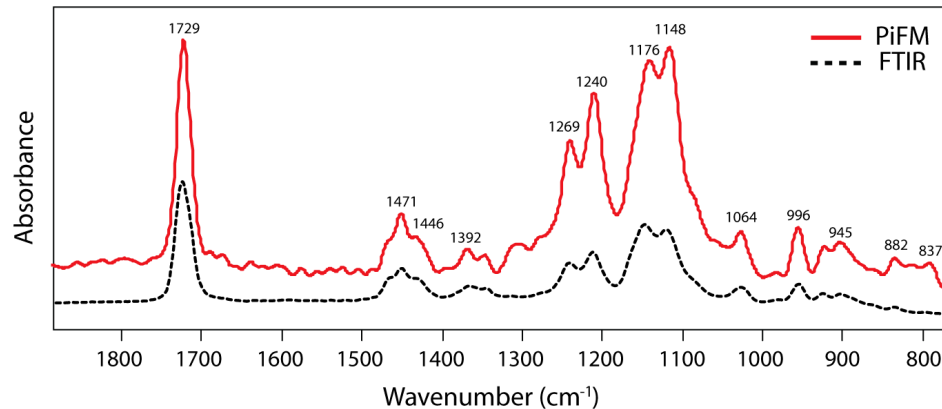
PiFM and FTIR of Nylon



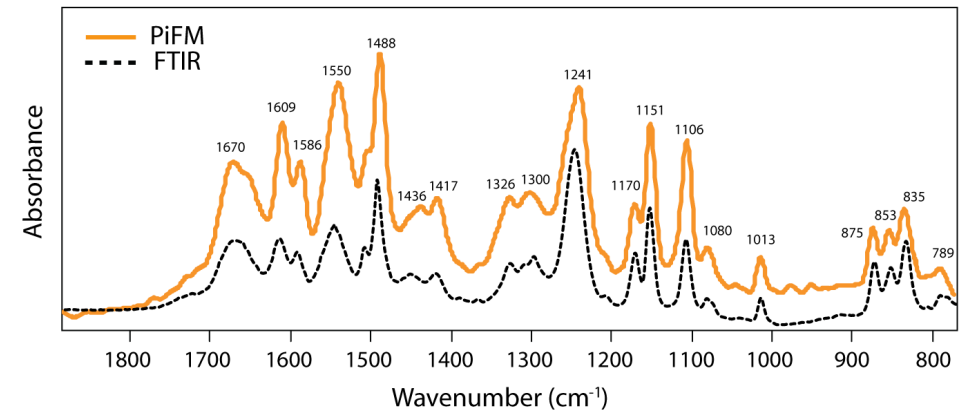
PiFM and FTIR of PES (Polyethersulfone)



PiFM and FTIR of PMMA - Poly(methyl methacrylate)



PiFM and FTIR of Polyimide

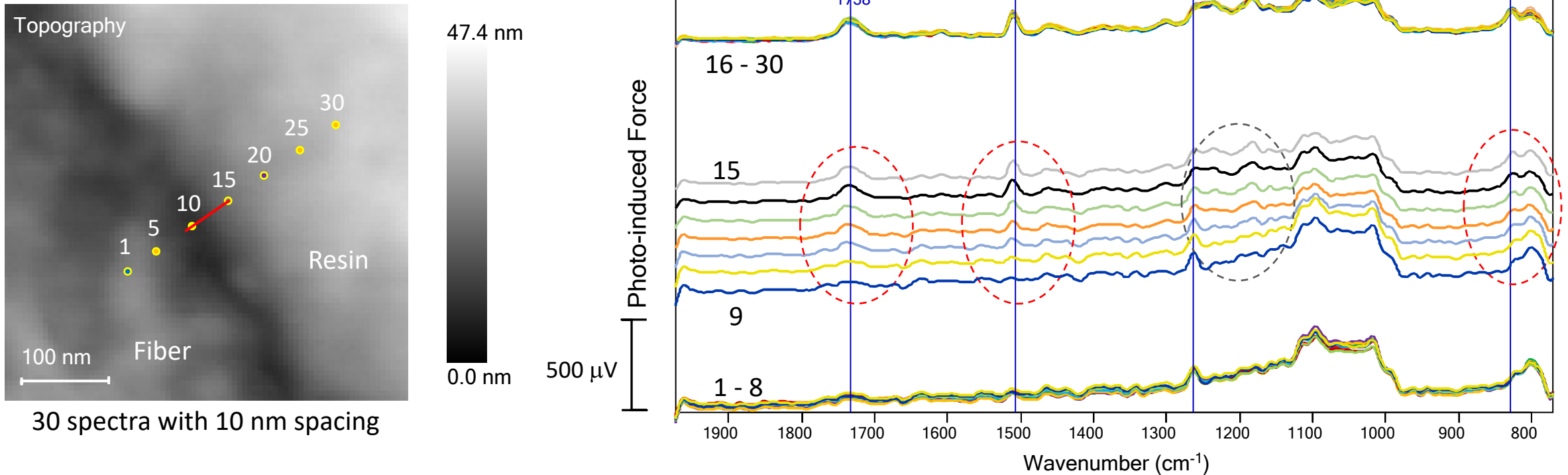


Excellent agreement between PiF-IR spectra (originating from ~ 5 nm region) and FTIR spectra (originating from ~ 10 μ m region) on homogeneous samples.



Excellent Repeatability

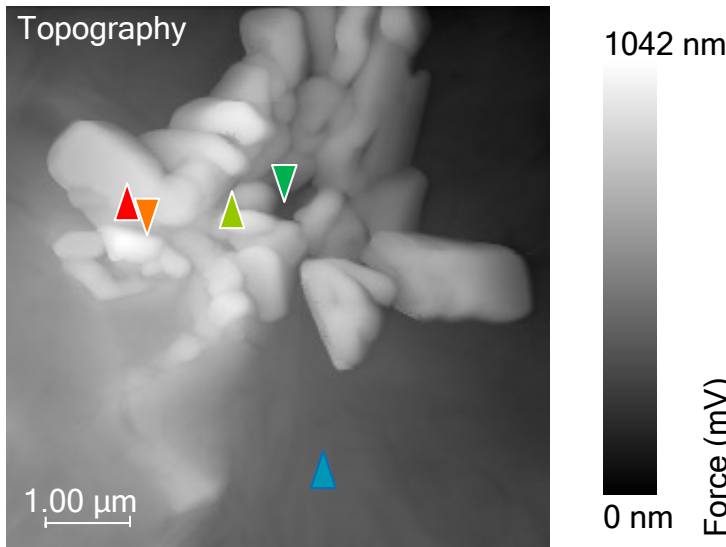
Carbon Fiber-Resin Interface



The interface between a carbon fiber and resin are analyzed by preparing a cross-section of the composite fiber via microtome. 30 PiF-IR spectra are acquired across the interface with ~ 10 nm spacing. The first 8 spectra in the carbon fiber and the last 16 – 30 spectra are very repeatable, with all the spectral changes taking place over 9 – 15 spectra. The SNR is good enough to discern chemical changes for each 10 nm changes in spatial location.

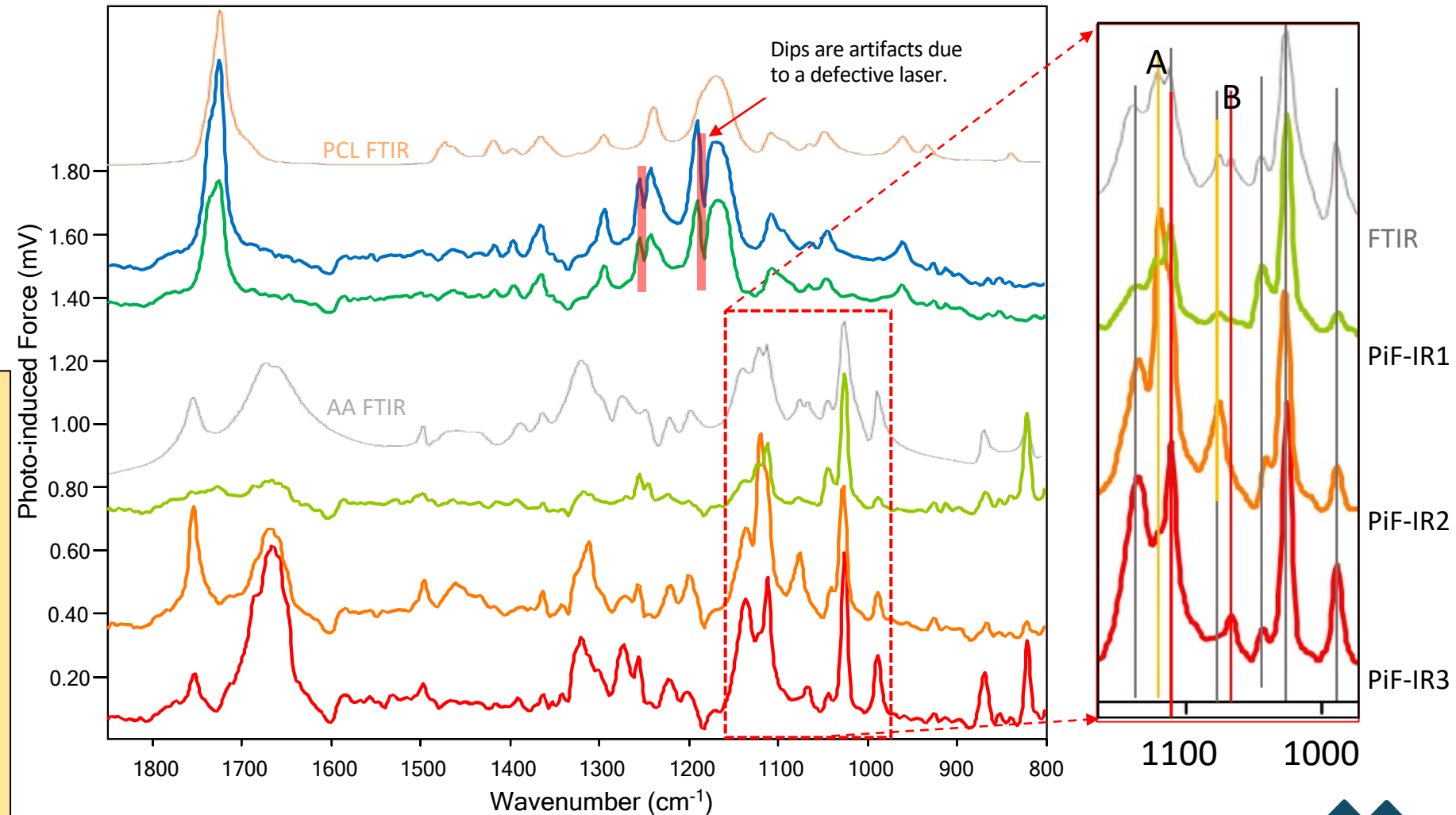


Discrimination of Molecular Orientation

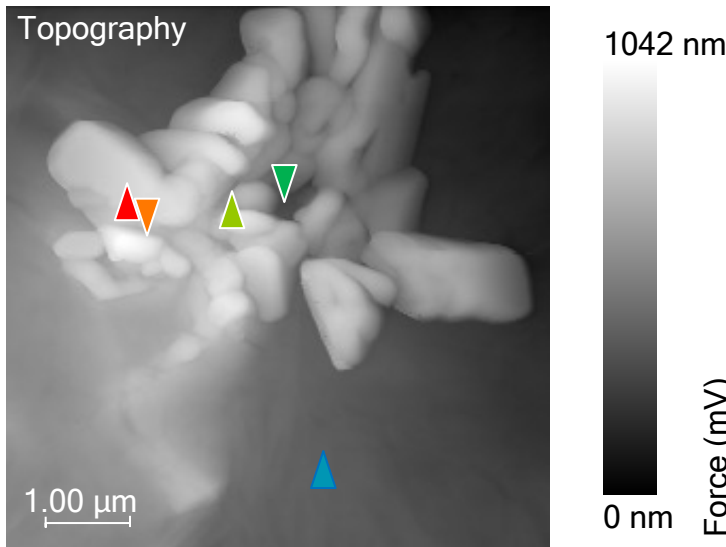


The two spectra (blue and dark green) on homogeneous PCL match the PCL FTIR well. The three spectra acquired on the AA crystals show different peak strengths compared to the AA FTIR. PiF-IR is most sensitive to modes that are out of the sample plane. As such, PiF-IR spectra on different crystal orientations highlight different peaks compared to FTIR, which is an ensemble average of billions of PiF-IR spectra. Note that for the FTIR doublets A and B, the red and orange spectrum each showcase different singlets.

Poly(e-Caprolactone)/Ascorbic Acid (PCL/5AA) – AA Crystals

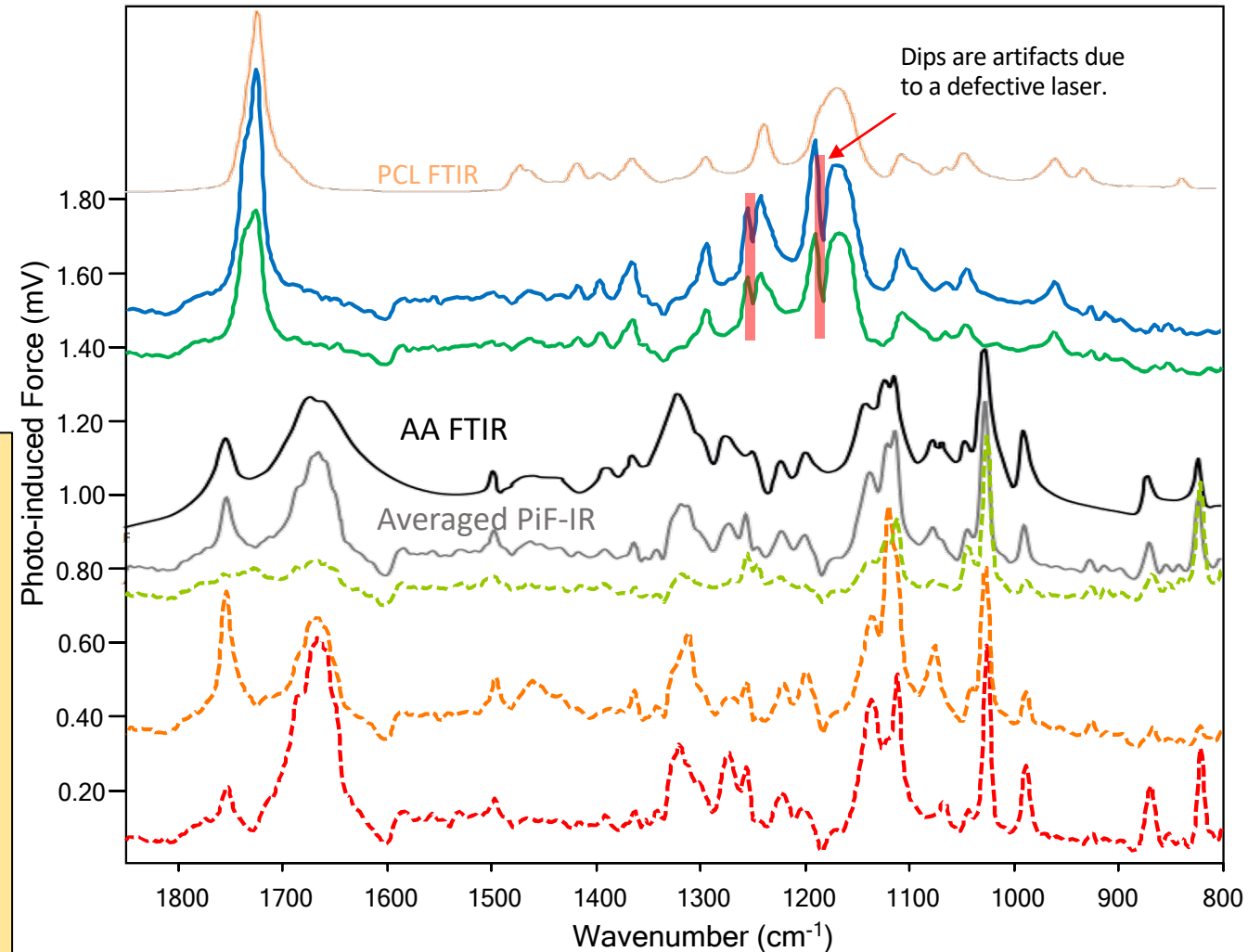


Discrimination of Molecular Orientation

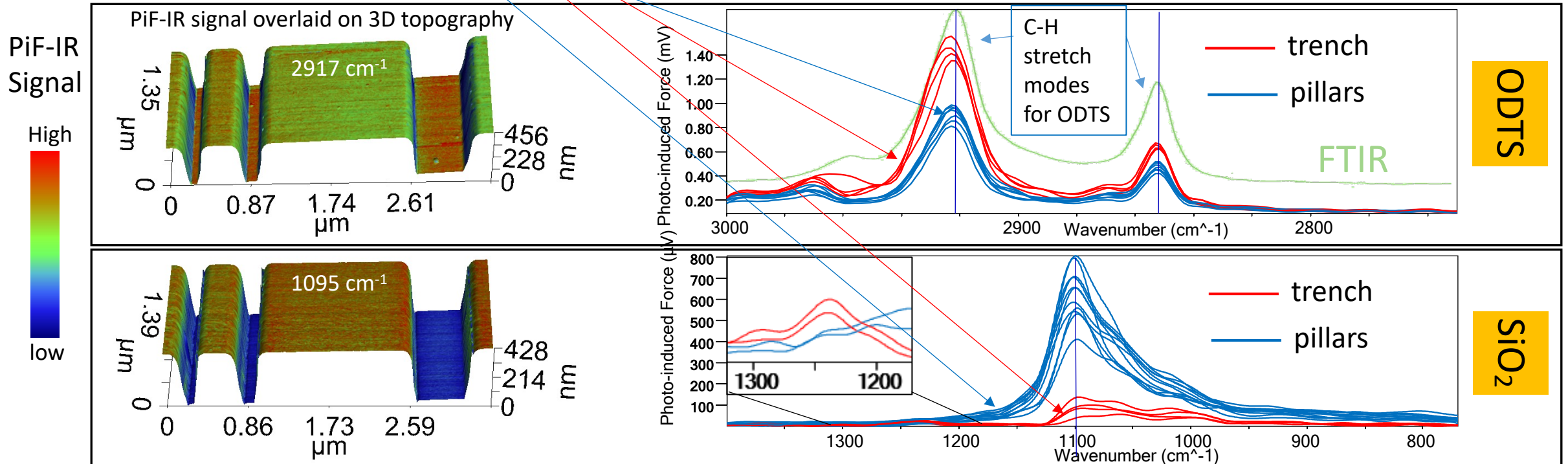
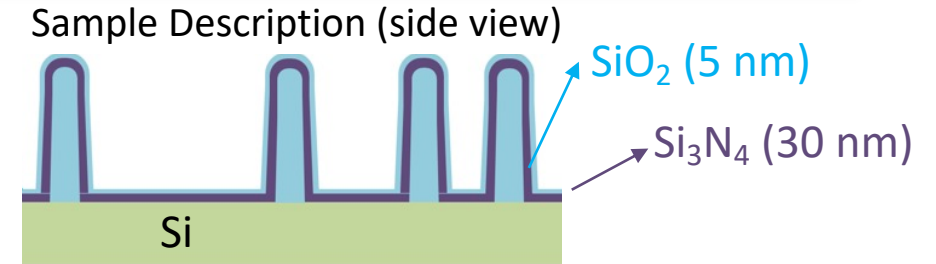
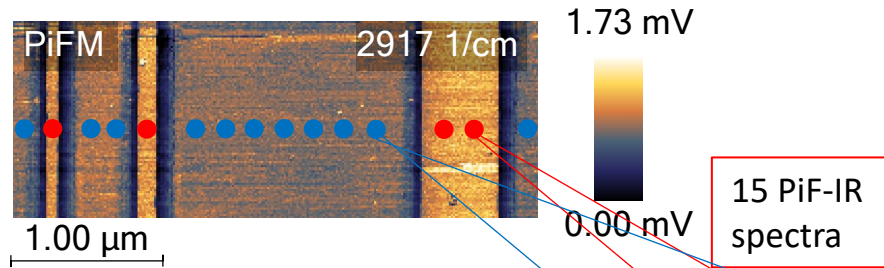


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Ensemble averaged FTIR versus local PiF-IR spectra



ODTS on SiO₂ (Organic & Inorganic Films)



Octadecyltrichlorosilane (ODTS) molecules are self-assembled on top of a 5nm-thick SiO₂. ODTs SAM layer is thin enough that PiF-IR spectra for the SiO₂ (bottom panel) can be acquired through the SAM layer. Note that the spectra for SiO₂ are different for the pillars (blue) and trenches (red), indicating different forms of SiO₂. As a results, higher packing density of ODTs (upper panel) is observed for the trenches.

Defects and Residue

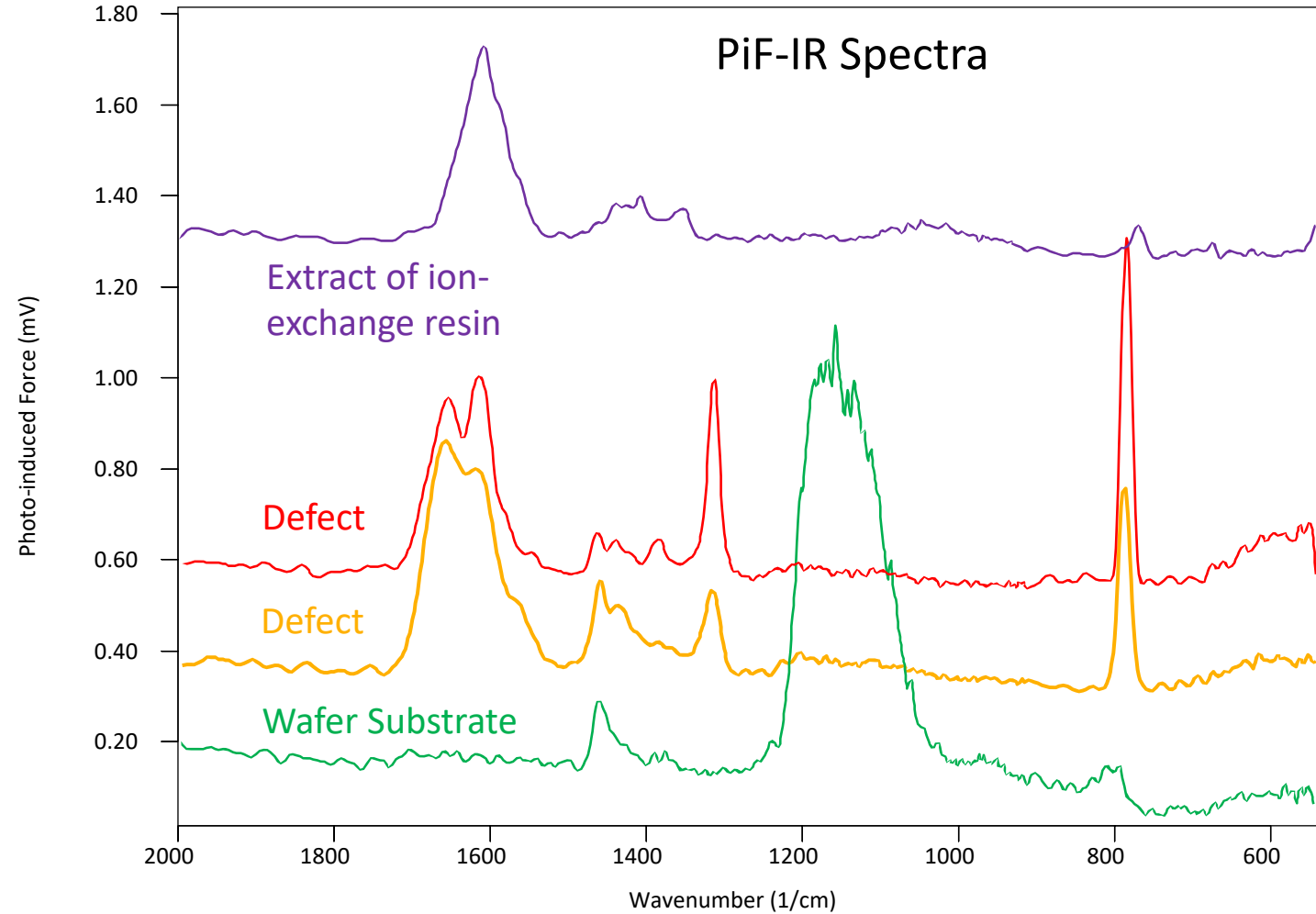
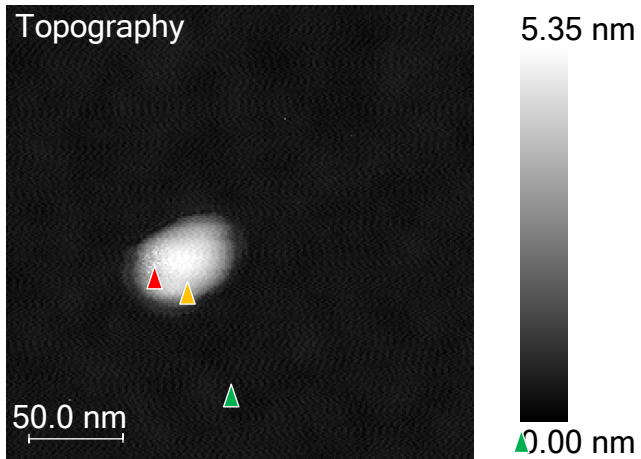


Defect/Residue on Wafer Processed by Ultrapure Water

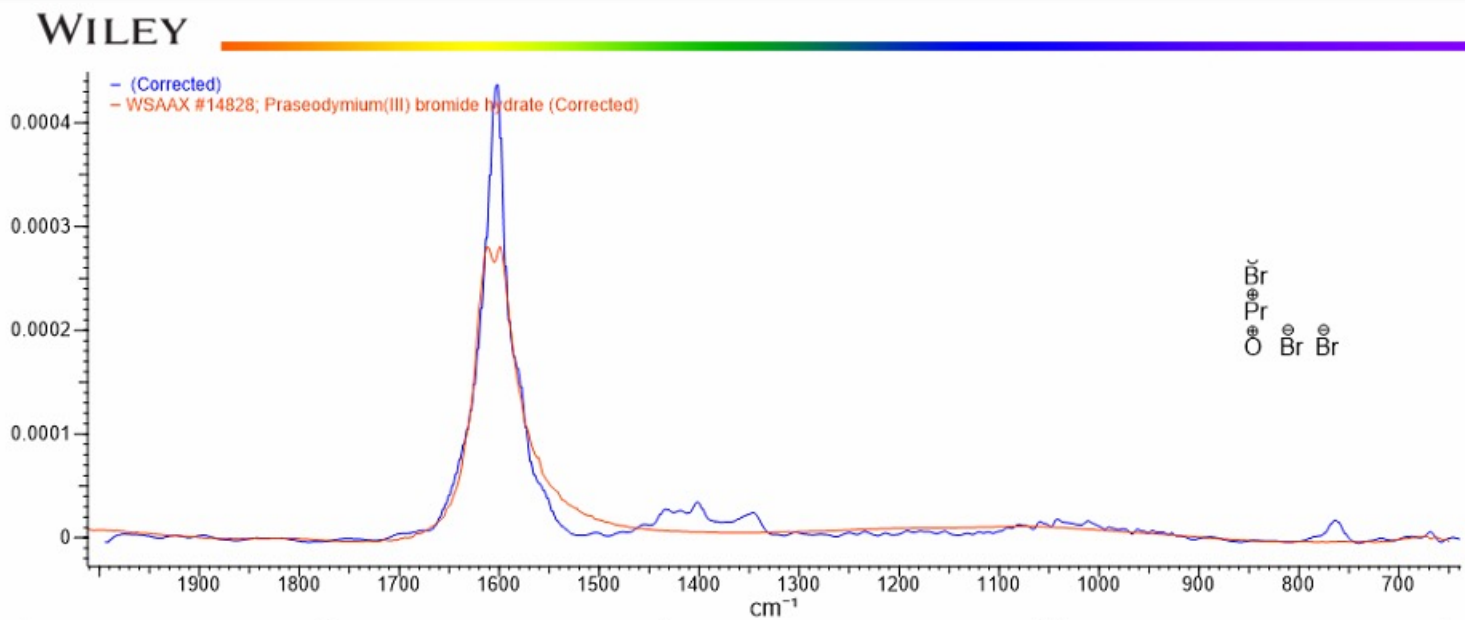
Extract of ion-exchange resin drop-cast on glass



Defect on wafer




One Component Search - Resin



About Cobalt(II) Bromide Hydrate

Most metal bromide compounds are water soluble for uses in water treatment, chemical analysis and in ultra high purity for certain crystal growth applications.

 American Elements
<https://www.americanelements.com/cobalt-ii-bromide-hydrate>

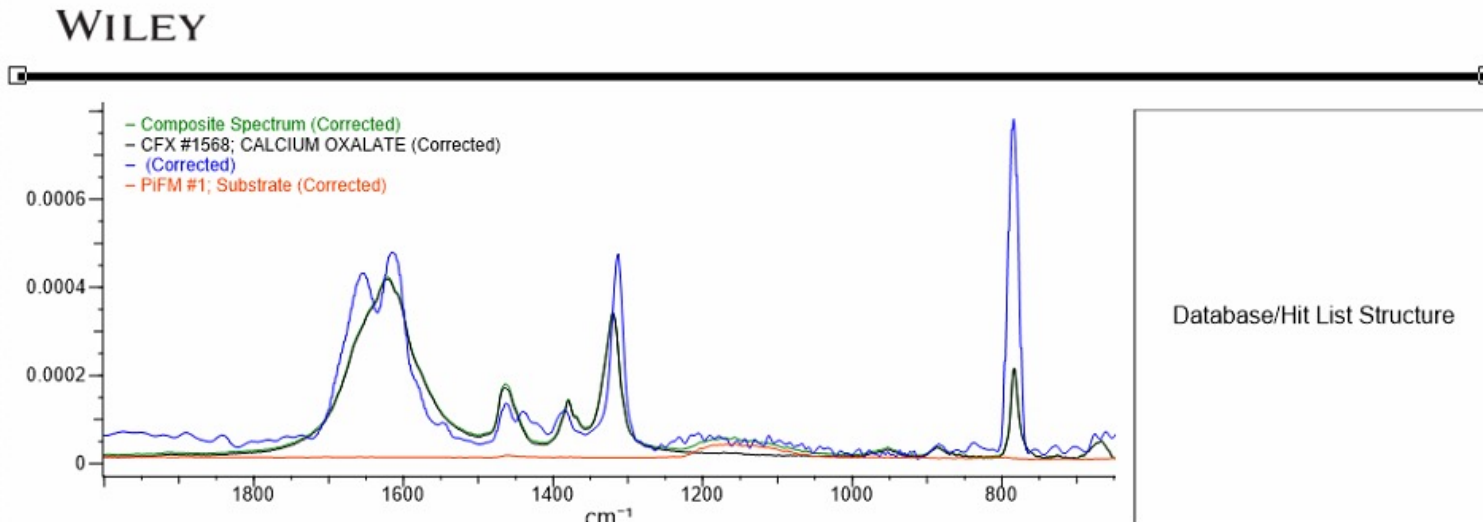
Cobalt(II) Bromide Hydrate | AMERICAN ELEMENTS®

Name		Value	
Name		Praseodymium(III) bromide hydrate	
CAS Registry Number		225505-12-4	
Catalog Number		575267	
Comments		MW calculated on anhydrous base	
Exact Mass		377.662662 u	
Formula		PrBr3·xH2O	
InChI		InChI=1S/3BrH.O.Pr/h3*1H;;/q;;;+3/p-3	
InChIKey		OLPNCVJBIOCRHH-UHFFFAOYSA-K	
Molecular Weight		380.620 g/mol	
Purity		>=99.99% trace metals basis	
Source of Sample		Aldrich	
SpectraBase Compound ID		2G1jnOvJyLb	
Wiley ID		SIAL_ATR-IR_021740	

HQI	Tag	Correctio	DB	ID	Name	Spectrum
86.03			WSAAX	14828	Praseodymium(III) bromide hydrate	



Two Components Search – Defect (red spectrum)

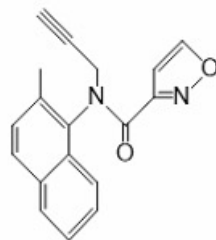
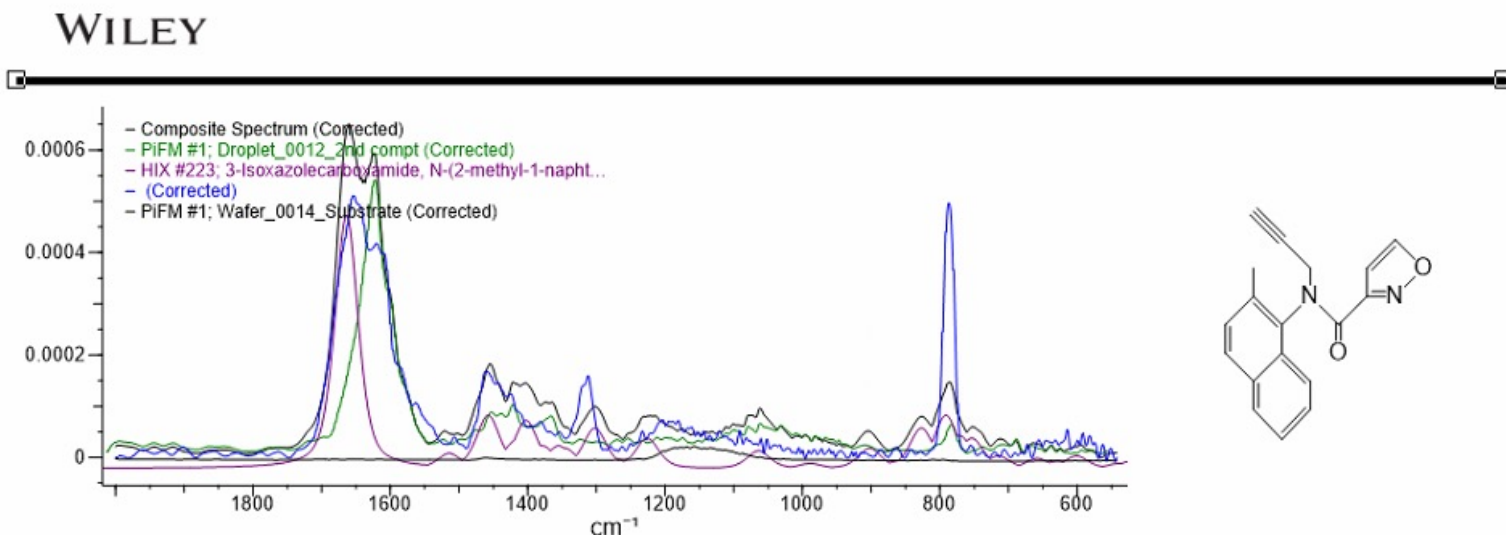


The result of the two components search for the defect 1 is same to the top result of the one component search.

HQI	Ratio	Exclude	recti	DB	ID	Name	Chemical Structure	Spectrum
65.84	N.A.					Composite Spectrum		
	0.92			CFX	1568	CALCIUM OXALATE		
	0.08					PiFM #1; Substrate		



Three Components Search – Defect (gold spectrum)



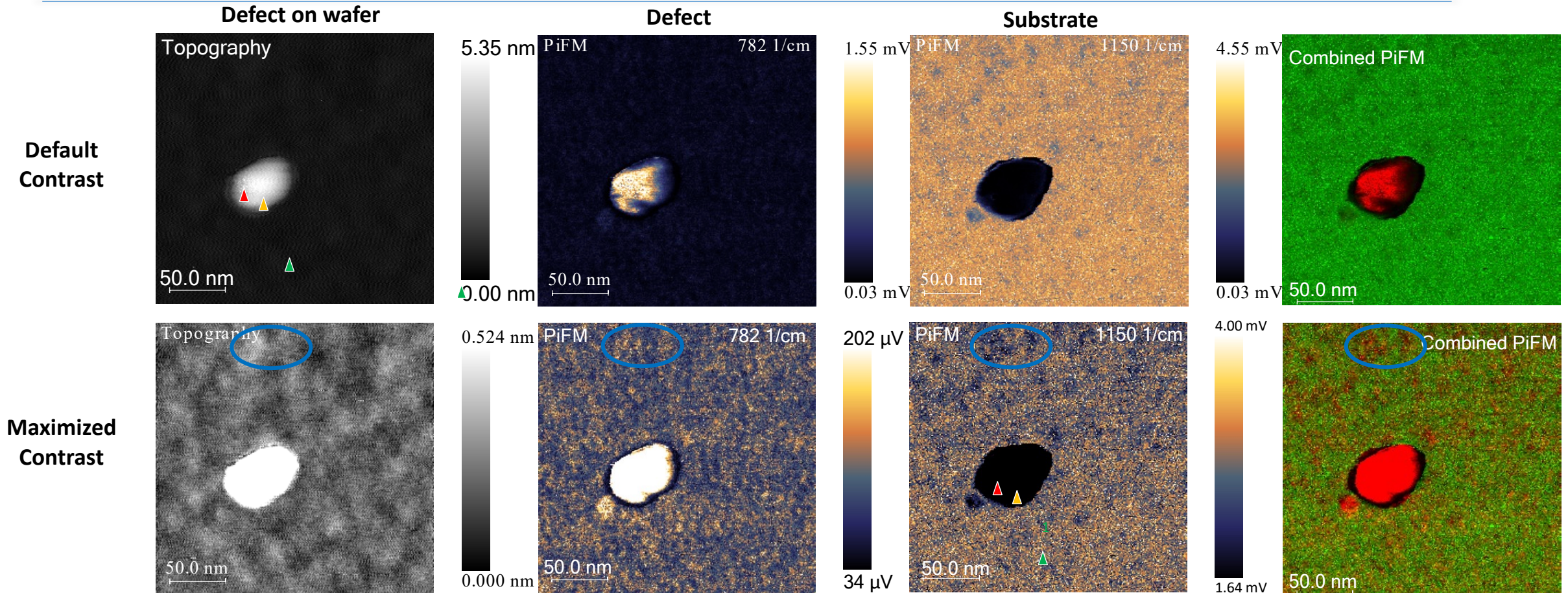
HQI	Ratio	Exclude	recti	DB	ID	Name	Chemical Structure	Spectrum
76.55	N.A.					Composite Spectrum		
	0.49					PiFM #1; Droplet_0012_2nd compt		
	0.48			HIX	223	3-Isoxazolecarboxamide, N-(2-methyl-1-naphthalenyl)-N-2-propynyl		
	0.03					PiFM #1; Wafer_0014_Substrate		

Structure/Properties

Substructs		Sel. Substructs	Original Data Files
All Properties		Attachments	Preferred Properties
Name	Value		
Name	3-Isoxazolecarboxamide, N-(2-methyl-1-naphthalenyl)-N-2-propynyl		
CAS Registry Number	86314-77-4		
Formula	C ₁₈ H ₁₄ N ₂ O ₂		



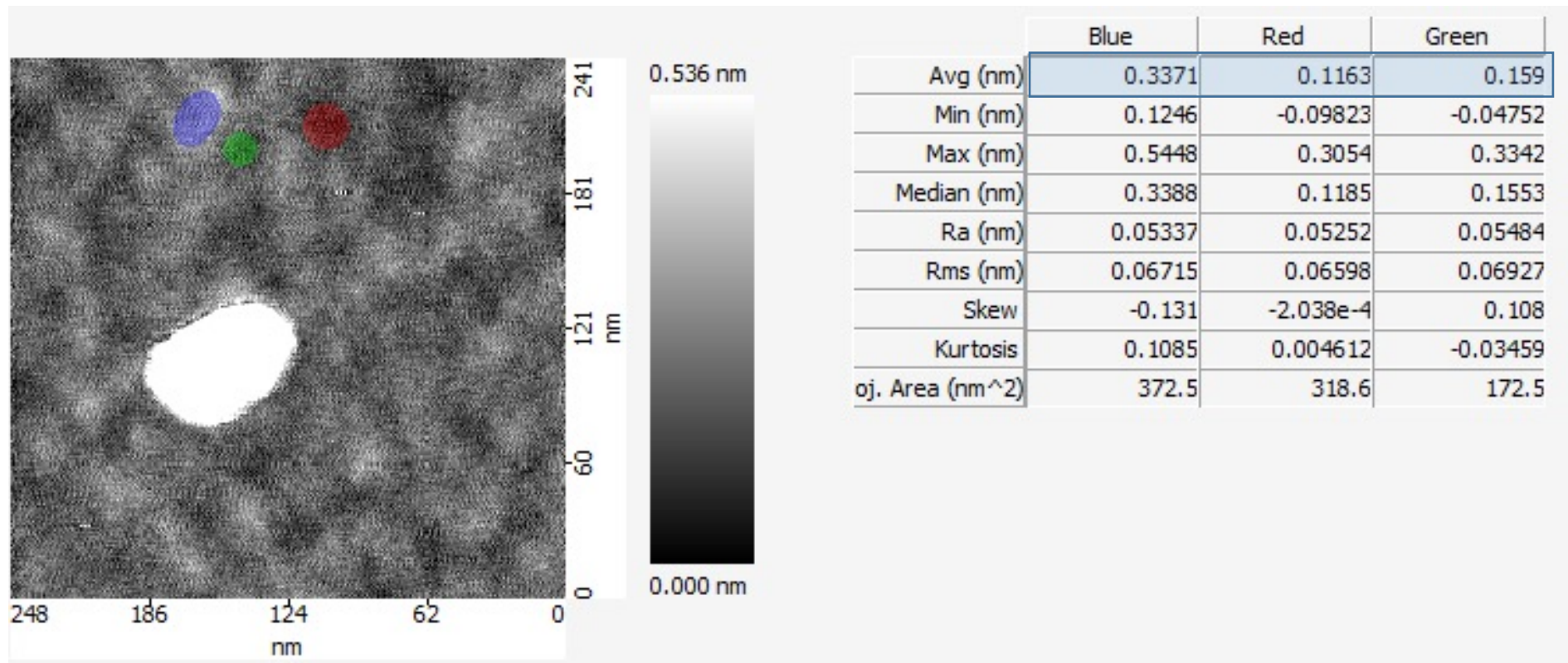
Analysis of Wafer Defect/Residue Processed by Ultrapure Water



The bottom row of images are the same as the top row but the contrast has been maximized to show the PiFM signal variation on the substrate. There are increases in signal at 782 cm^{-1} on the substrate where 1150 cm^{-1} decreases, and the topography height also increases slightly (blue circles). This suggests that there are also very thin layers of the defect on the substrate along with the larger defect. IR PiFM is surface sensitive, and any intervening residue between the substrate and the tip will reduce the signal strength of the substrate (in this case 1150 cm^{-1}).



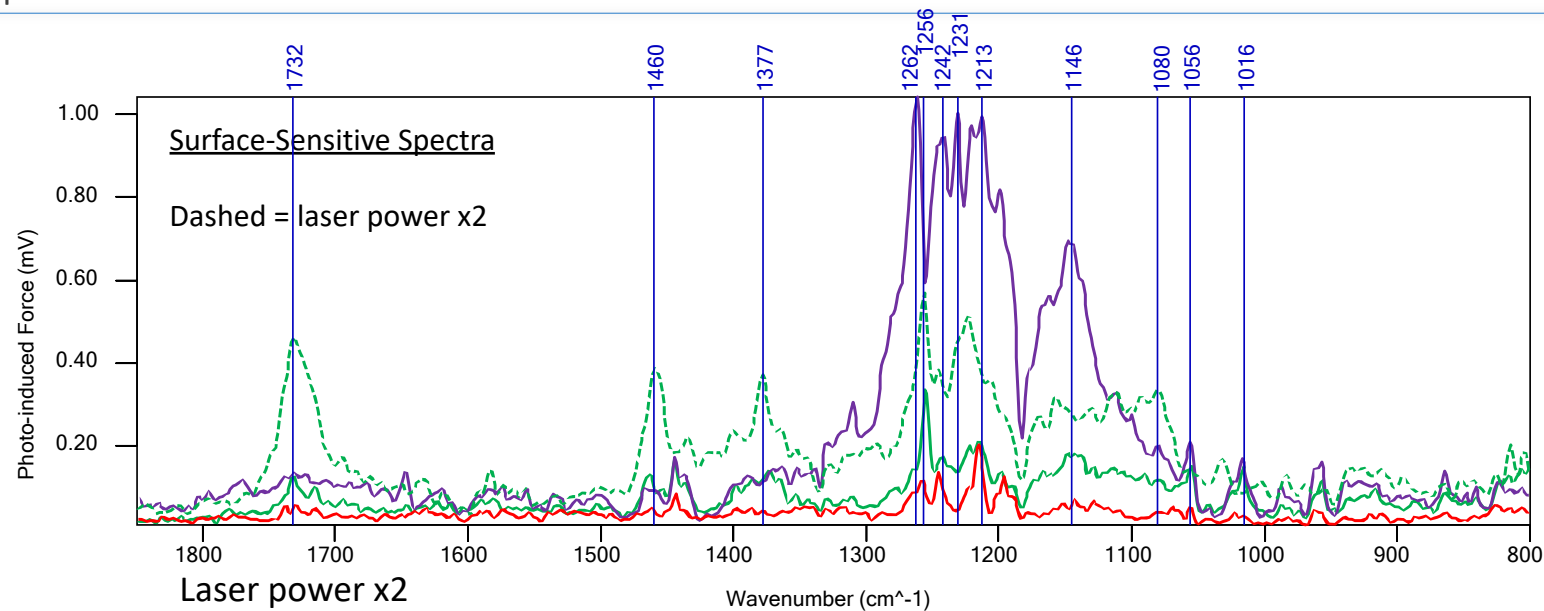
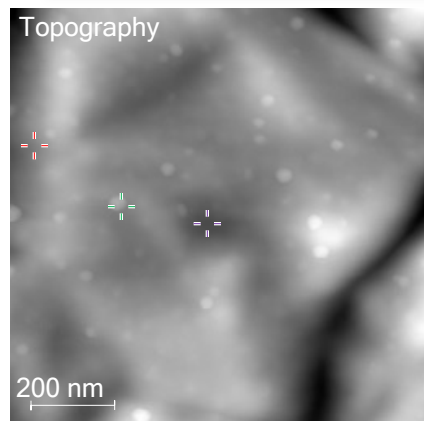
Analysis of Wafer Defect/Residue Processed by Ultrapure Water



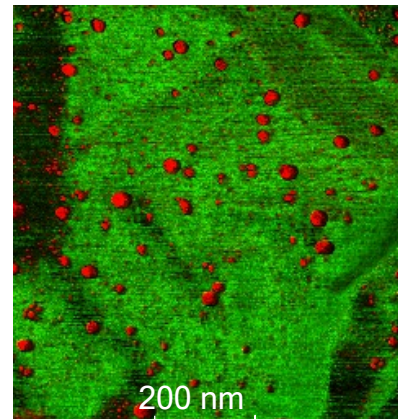
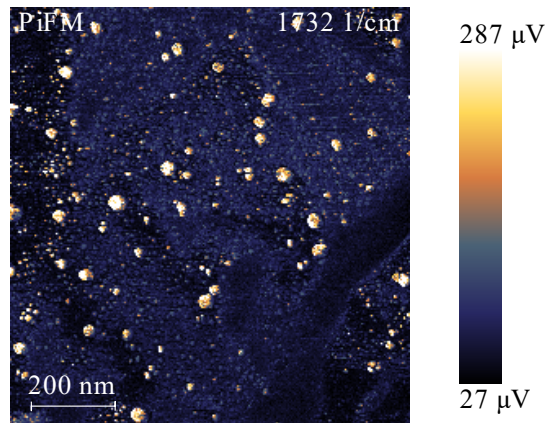
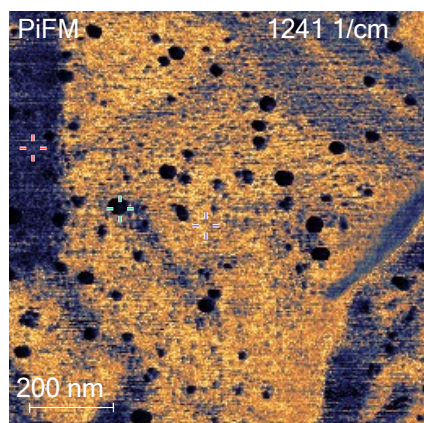
The average height of the residue seems to be about 0.2nm thick, which may indicate a monolayer.



Failure of Contact Pad Analyzed: $1\ \mu\text{m}^2$ Topography, PiFM and Spectra



The purple surface-sensitive spectrum shows similar peaks to those on the edge, well defined peaks at 1262, 1242, 1231, 1213 within the broad peak centered around 1230 cm^{-1} . However, the center shows additional contaminants, these are small particles found on the sample surface, with peaks around 1732, 1460, 1377, 1256 and 1225 cm^{-1} .



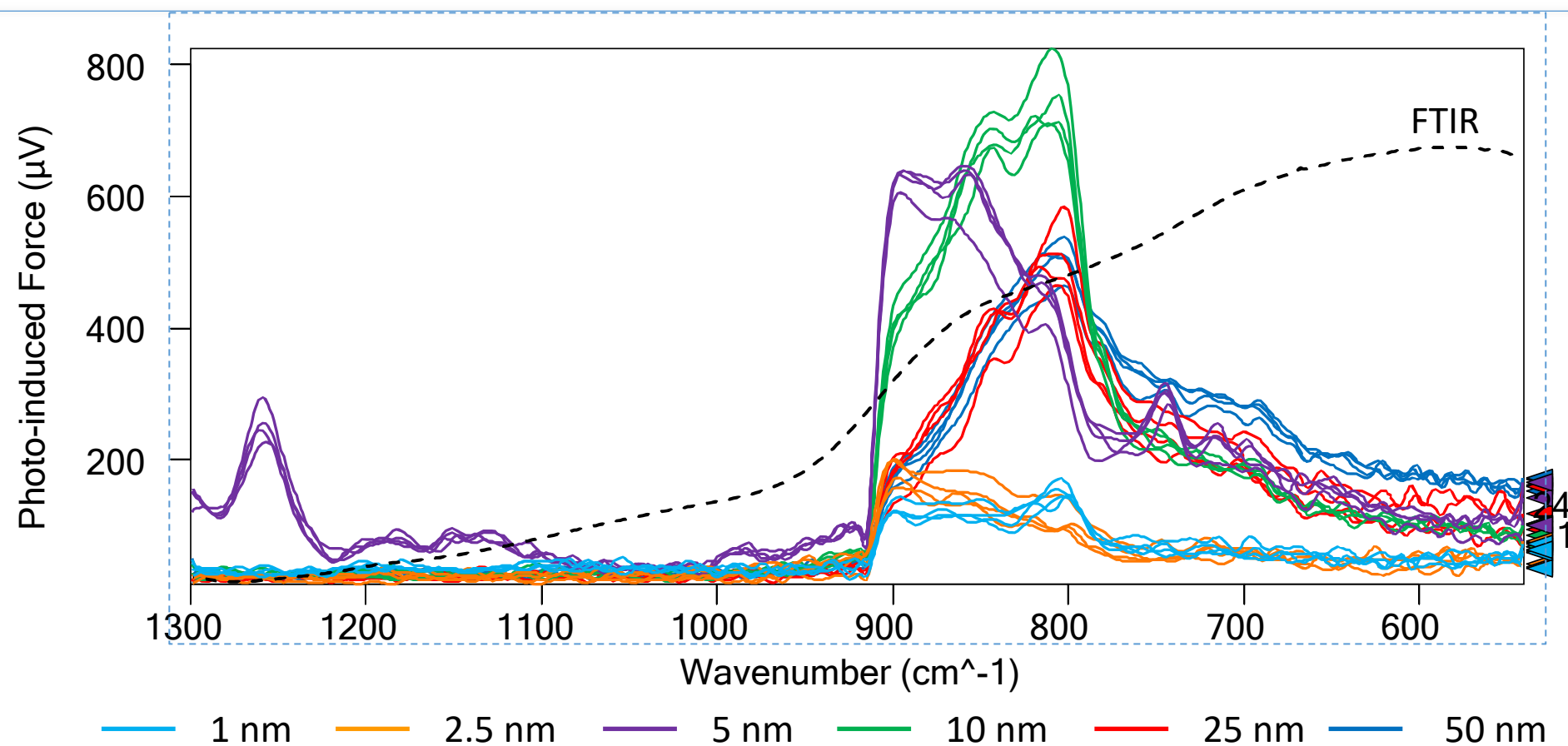
- C-F compound ($1241\ \text{cm}^{-1}$)
- 2nd contaminant ($1732\ \text{cm}^{-1}$)



ALD Films



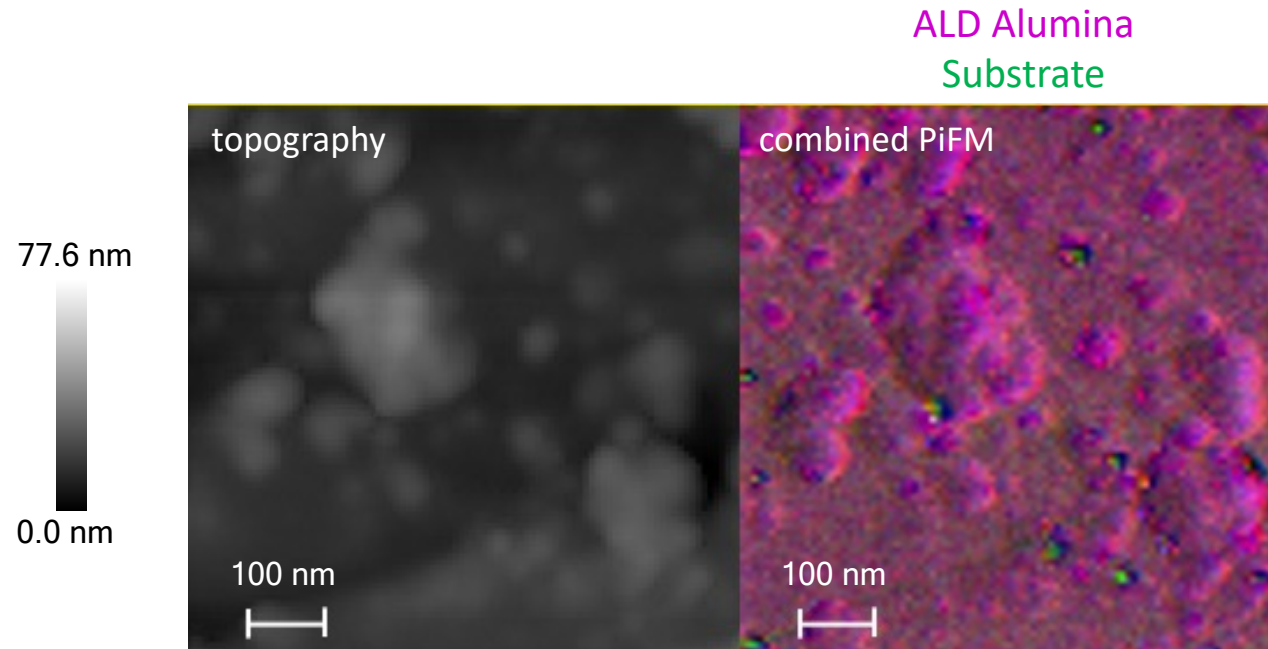
PiF-IR Analysis of ALD Grown Al_2O_3



Four spectra (1 μm spacing) are acquired from each sample; they are reasonably repeatable indicating that each sample is homogeneous. Compared to the broad FTIR spectrum, PiF-IR spectra display sharper features that vary with thickness.



PiFM Image of ALD Grown Al_2O_3



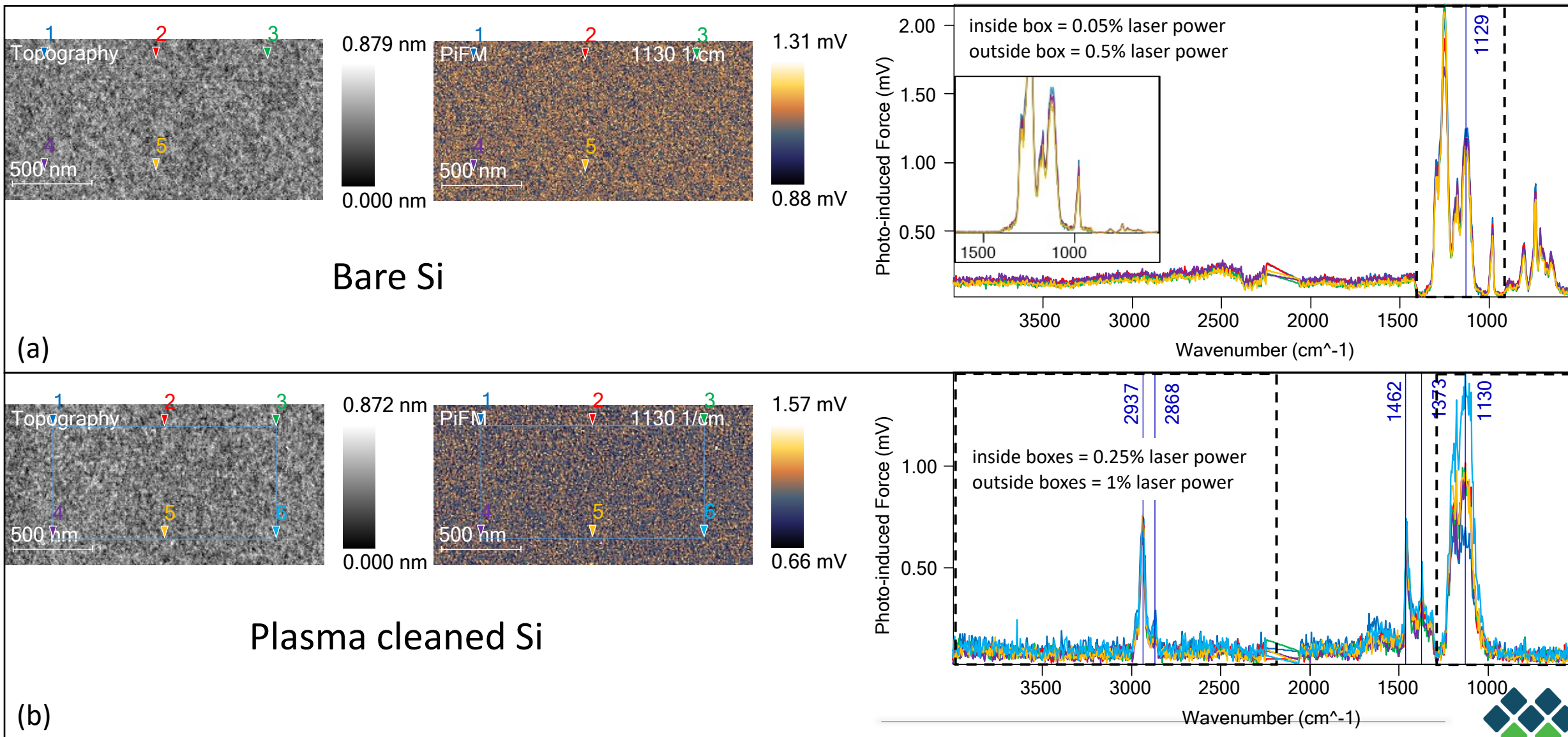
Alumina is grown on top of a substrate material via ALD and examined via IR PiFM. Topography is shown on the left. A combined PiFM image consisting of one PiFM image for alumina (purple) and another one for the substrate (green) clearly shows multiple pinholes (~ 10 nm in size) in the alumina layer.



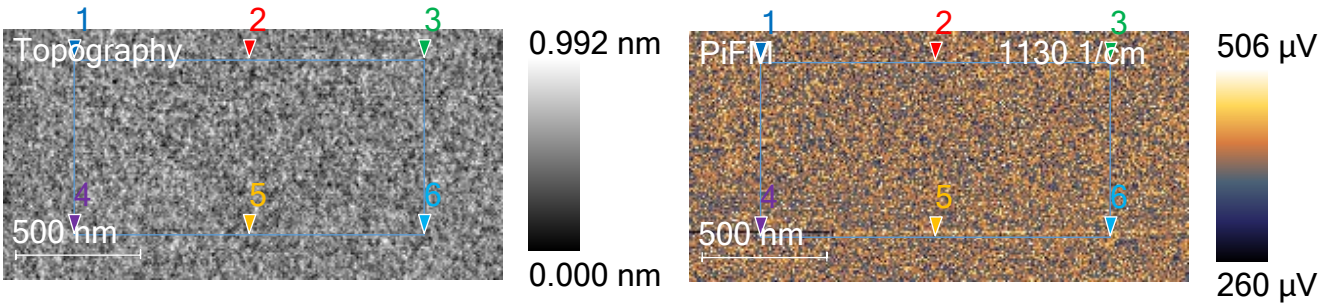
Surface Contaminations and Monolayers



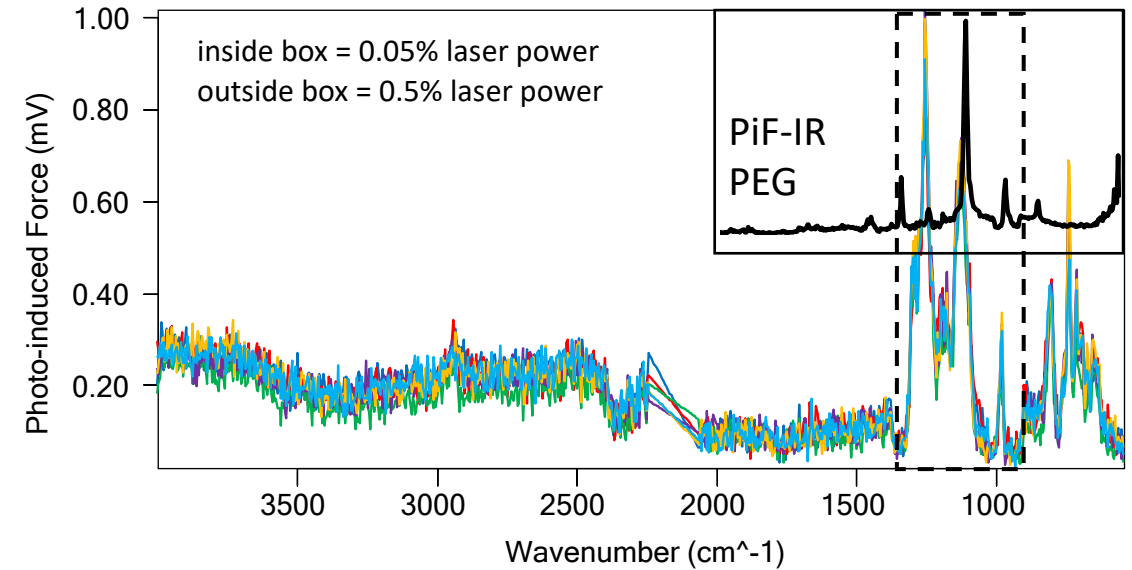
Organic Contaminants on Substrates



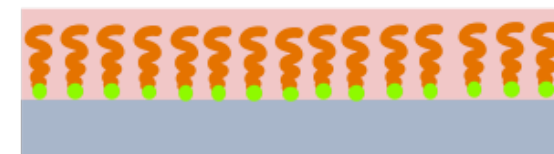
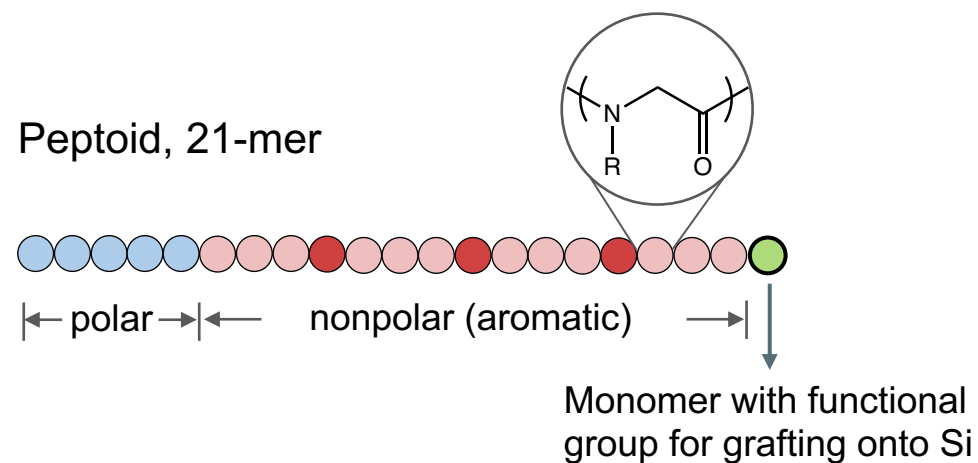
Unsuccessful monolayer of PEG on Si



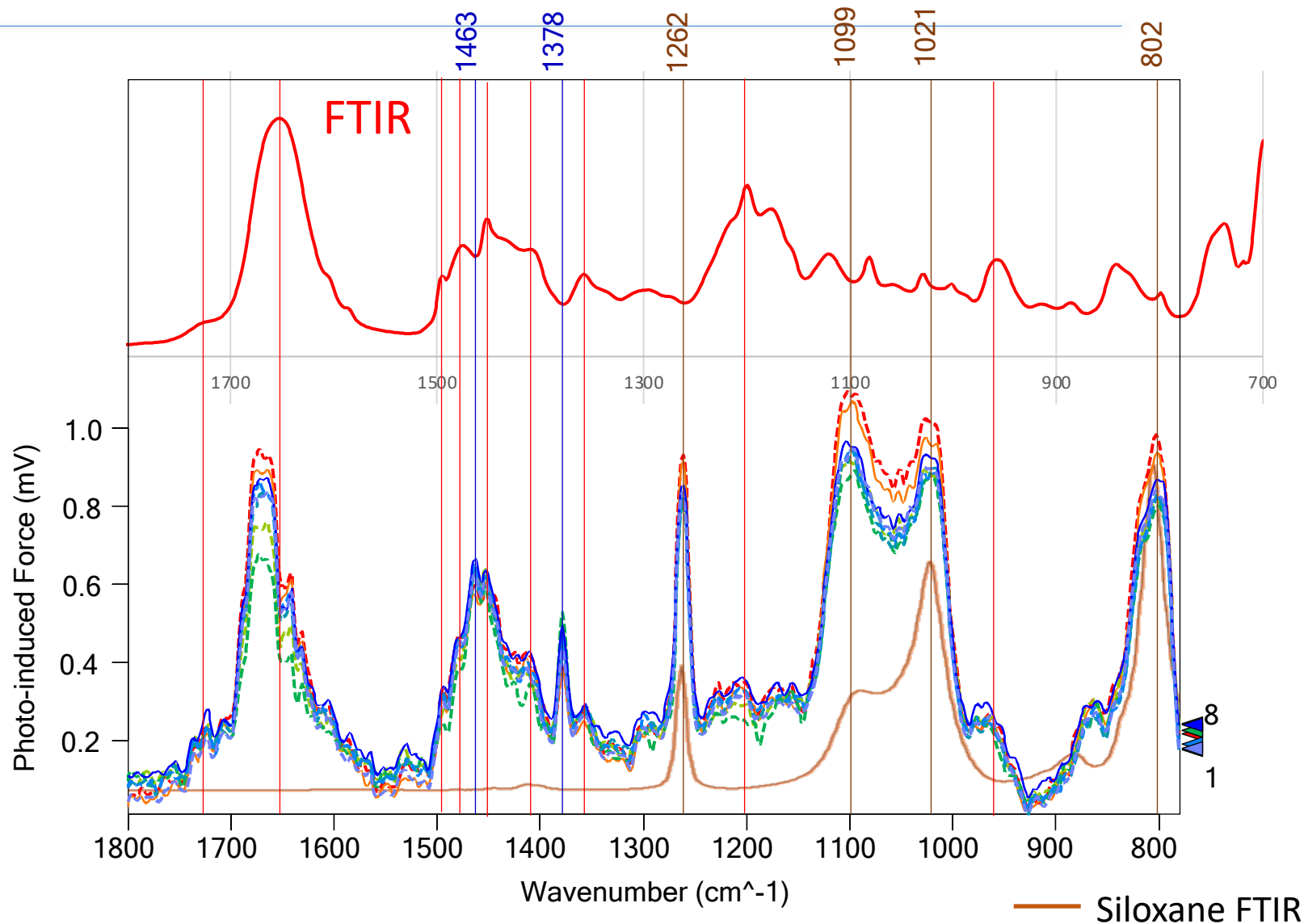
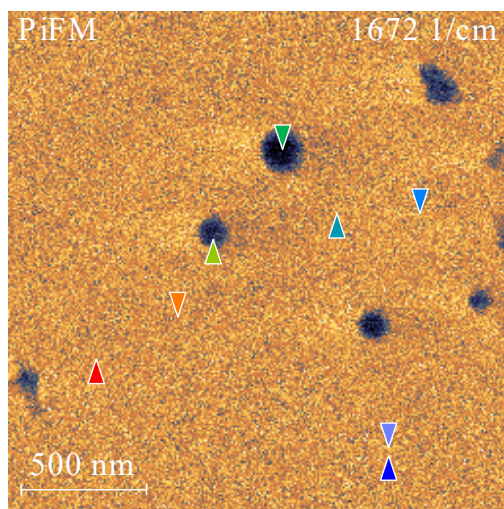
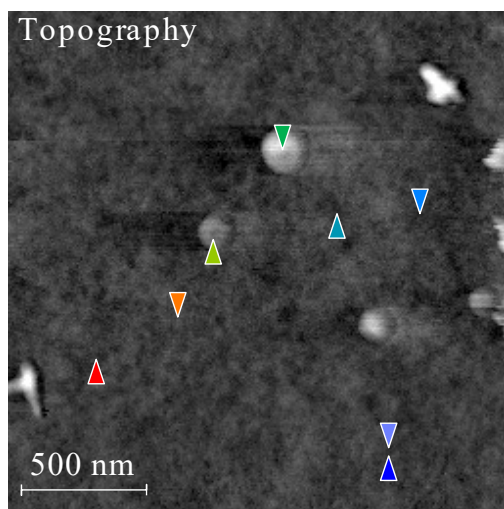
PEG on Si



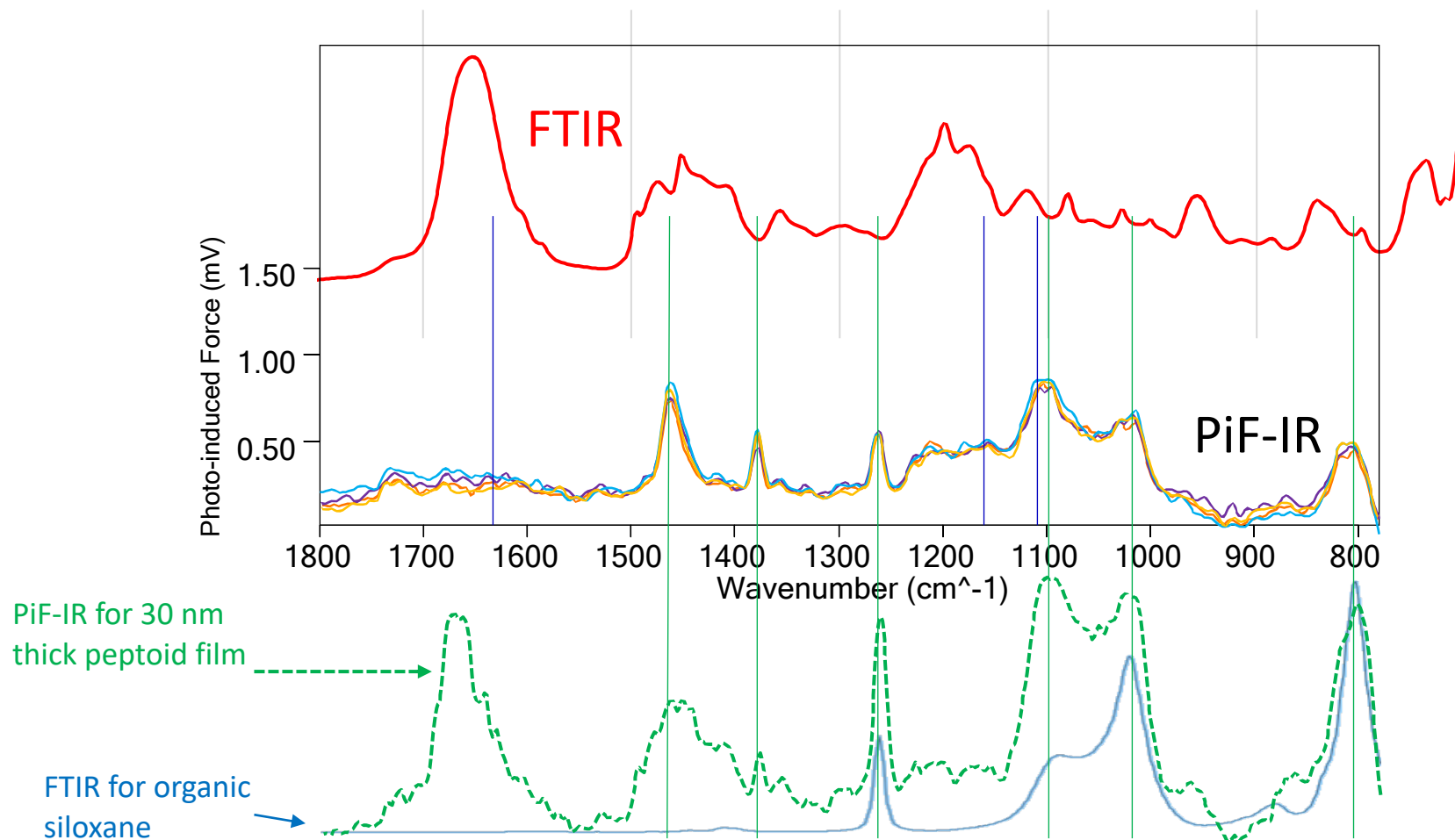
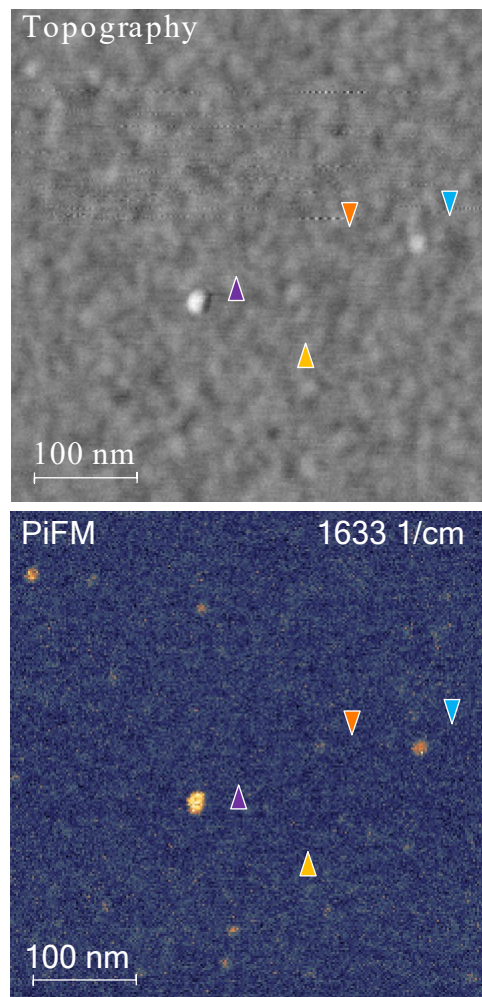
Monolayer of peptoid film



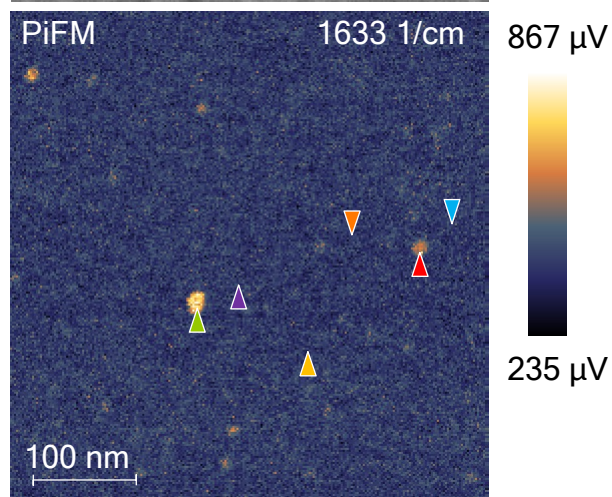
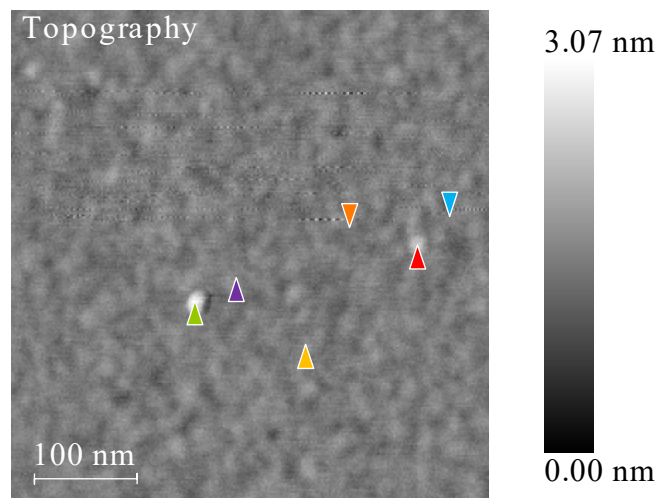
30 nm thick peptoid film



“Monolayer” of peptoid molecules

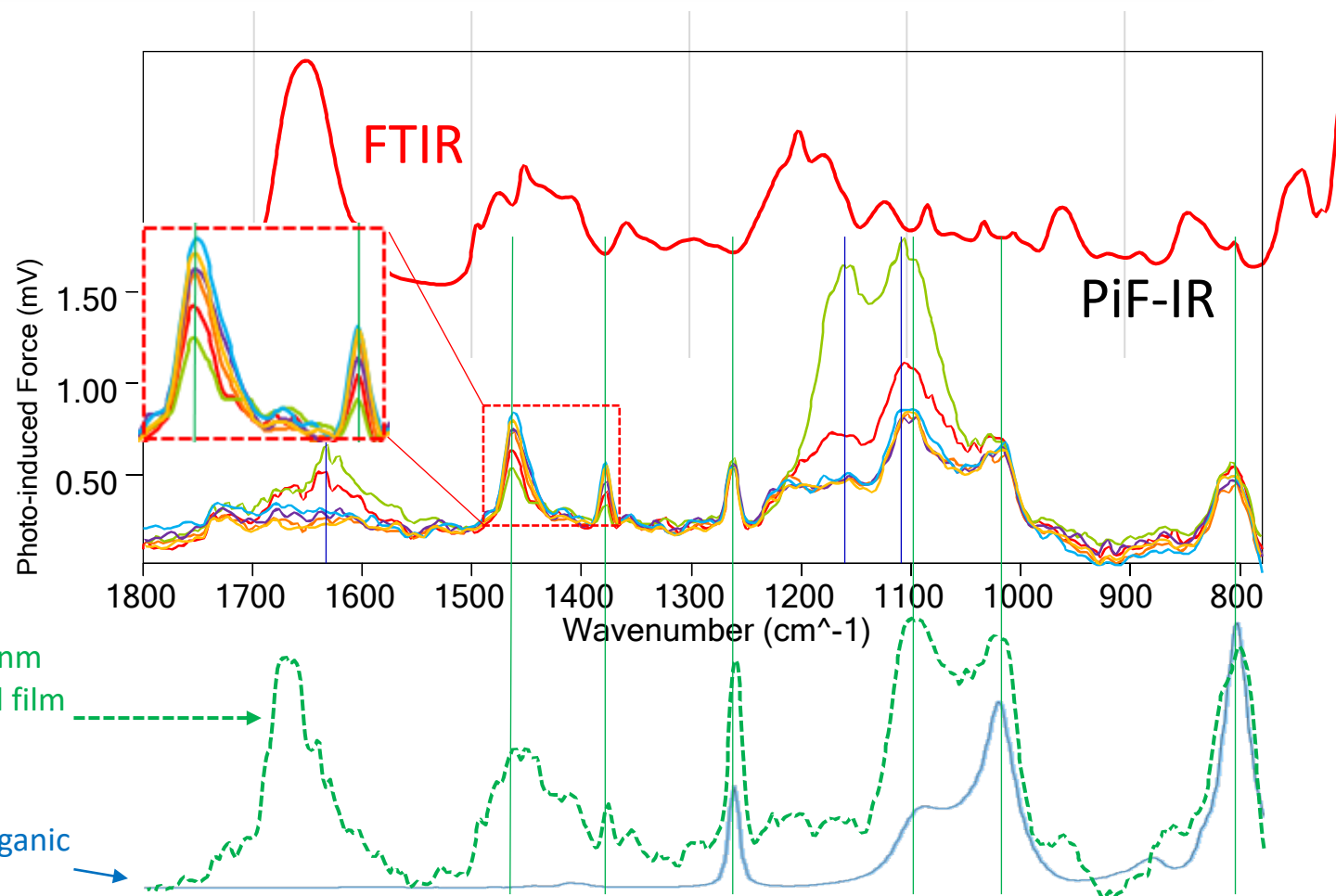


Only fragments of peptoid molecules



PiF-IR for 30 nm
thick peptoid film

FTIR for organic
siloxane

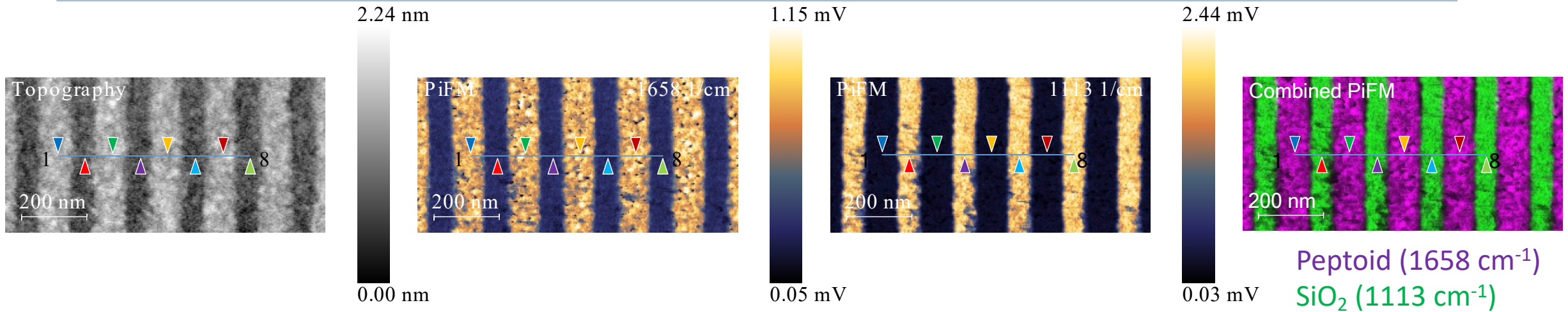


Height: 1.8 nm x Width: 16 nm

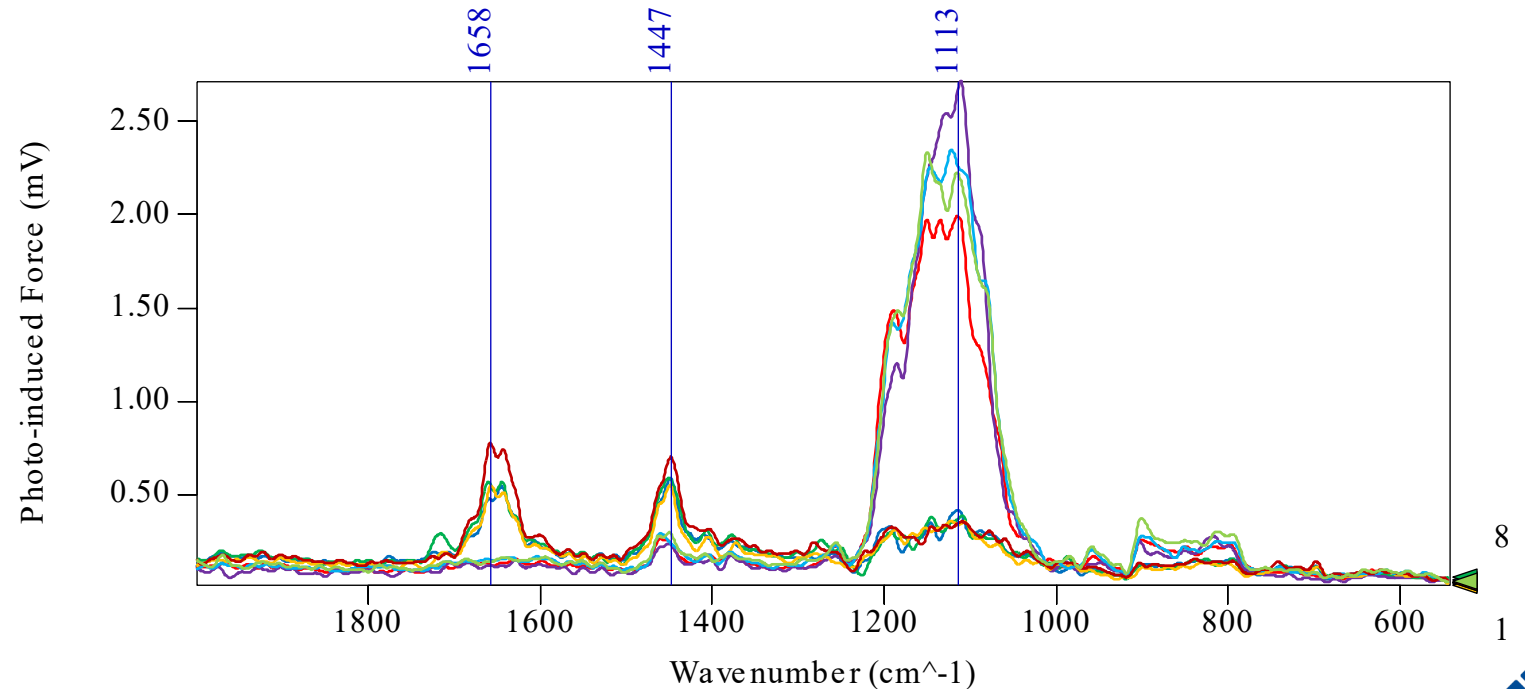
Height: 1.2 nm x Width: 16 nm



Monolayer of peptoid film patterned via e-beam lithography



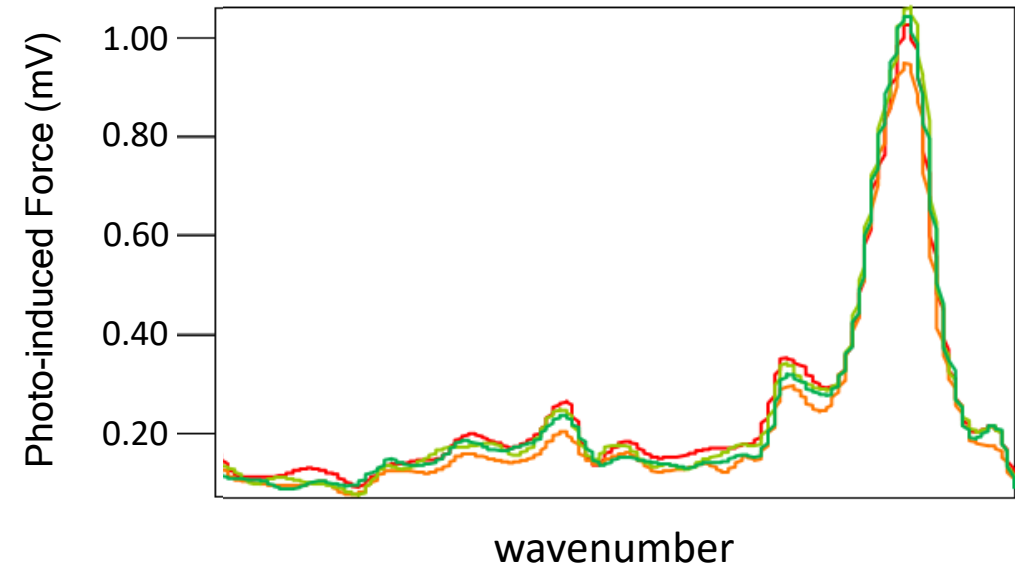
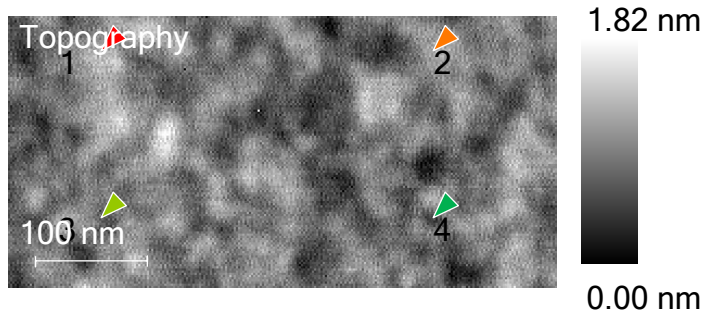
- All spectra on taller lines have peaks around 1658 and 1447 cm^{-1}
- The spectra on the substrate show strong peak around 1113 cm^{-1}
- Images clearly highlight peptoid lines (1658 cm^{-1}) and substrate (1113 cm^{-1})



Chemical Metrology of EUV Resist



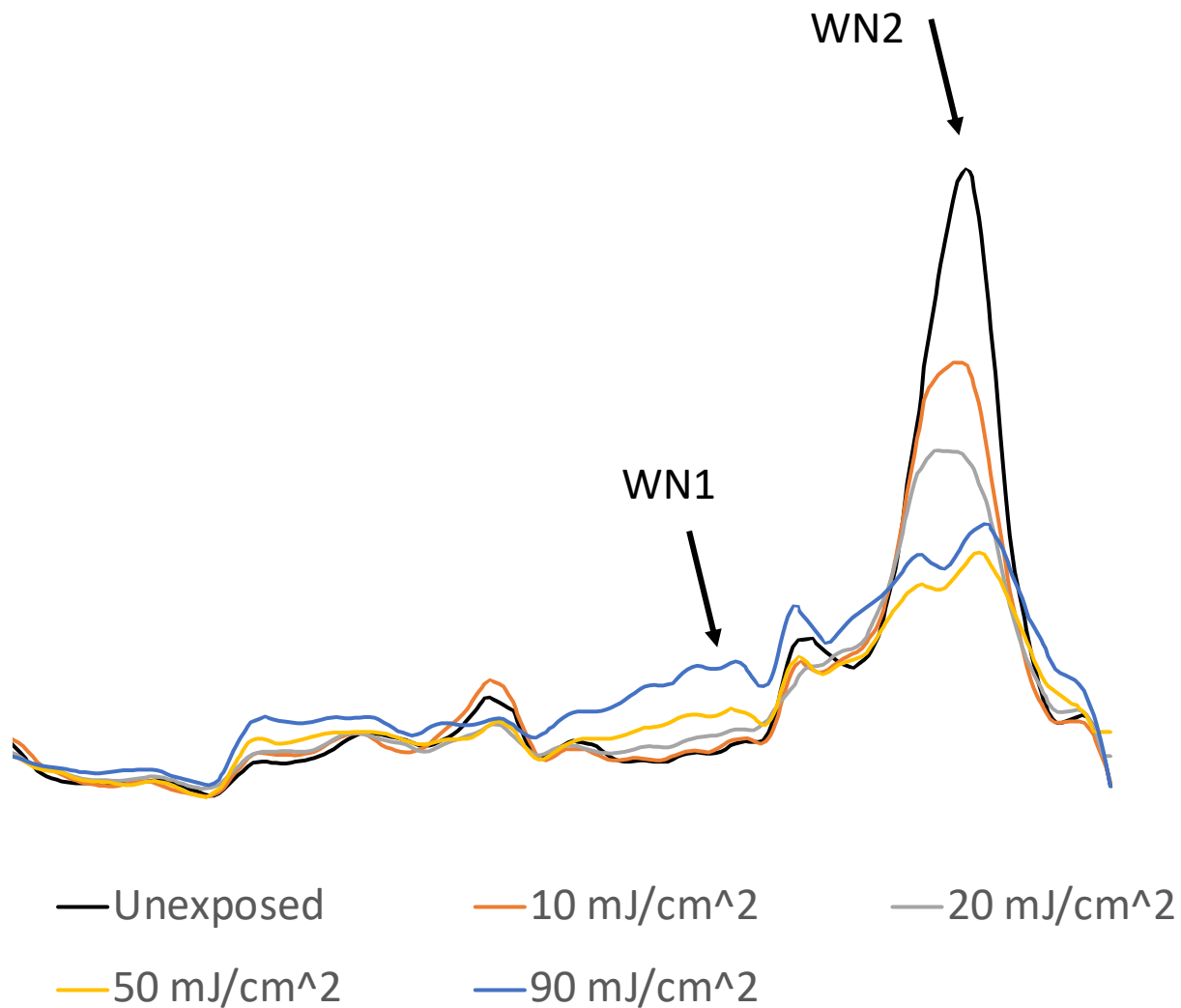
Multiple PiF-IR Spectra (Repeatability & Variability)



The repeatability of the four PiF-IR spectra at different locations is decent and indicates that the chemical composition of the metal oxide EUV resist is reasonably homogeneous. The values of the wavenumbers are hidden per manufacturer's request.



Comparison of Averaged PiF-IR Spectra with Exposure



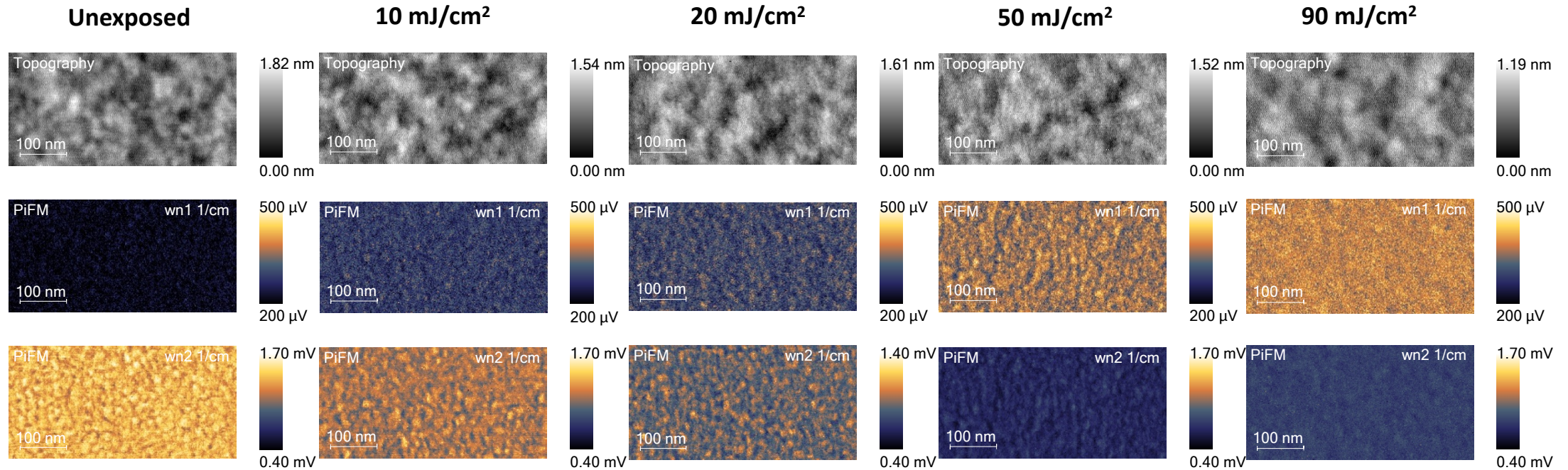
EUV resists exposed at four dose values are analyzed via PiF-IR spectra. Four spectra are acquired at each dose as in the reference resist (unexposed) and averaged for comparison.

A reduction in PiF signal @WN2 is observed with exposure while an increase in PiF signal at WN1 is observed with exposure.

PiFM images are acquired at these two wavenumbers and presented in the next slide.



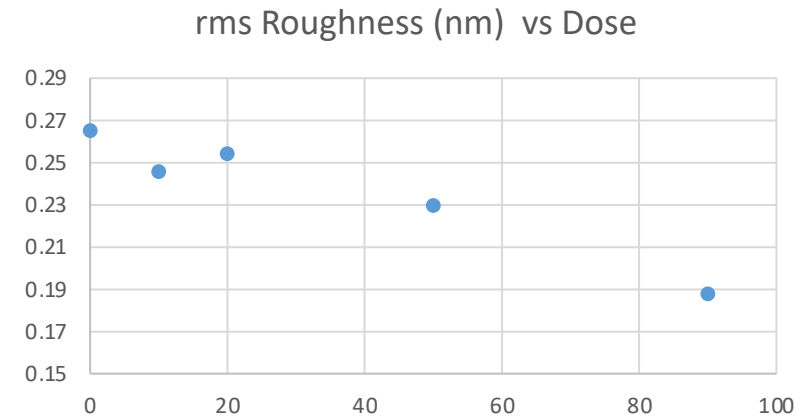
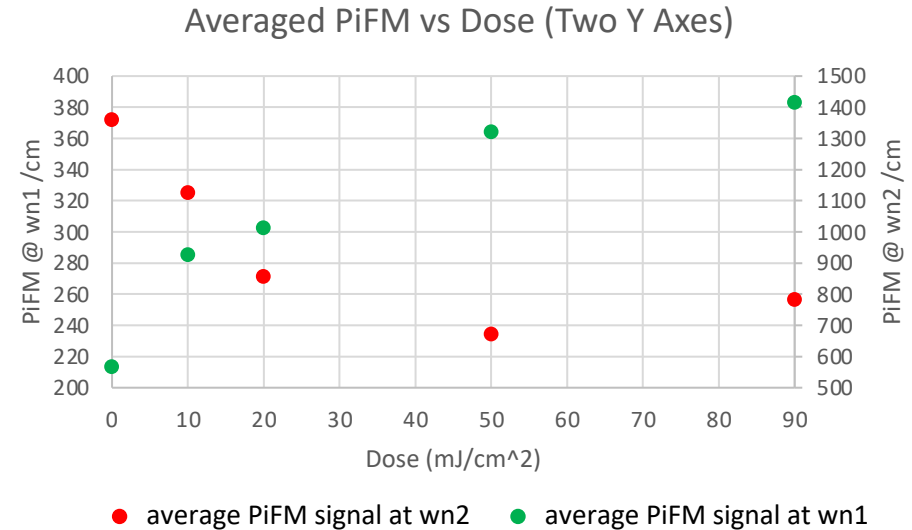
PiFM Images of Metal Oxide EUV Resist @ Different Exposure



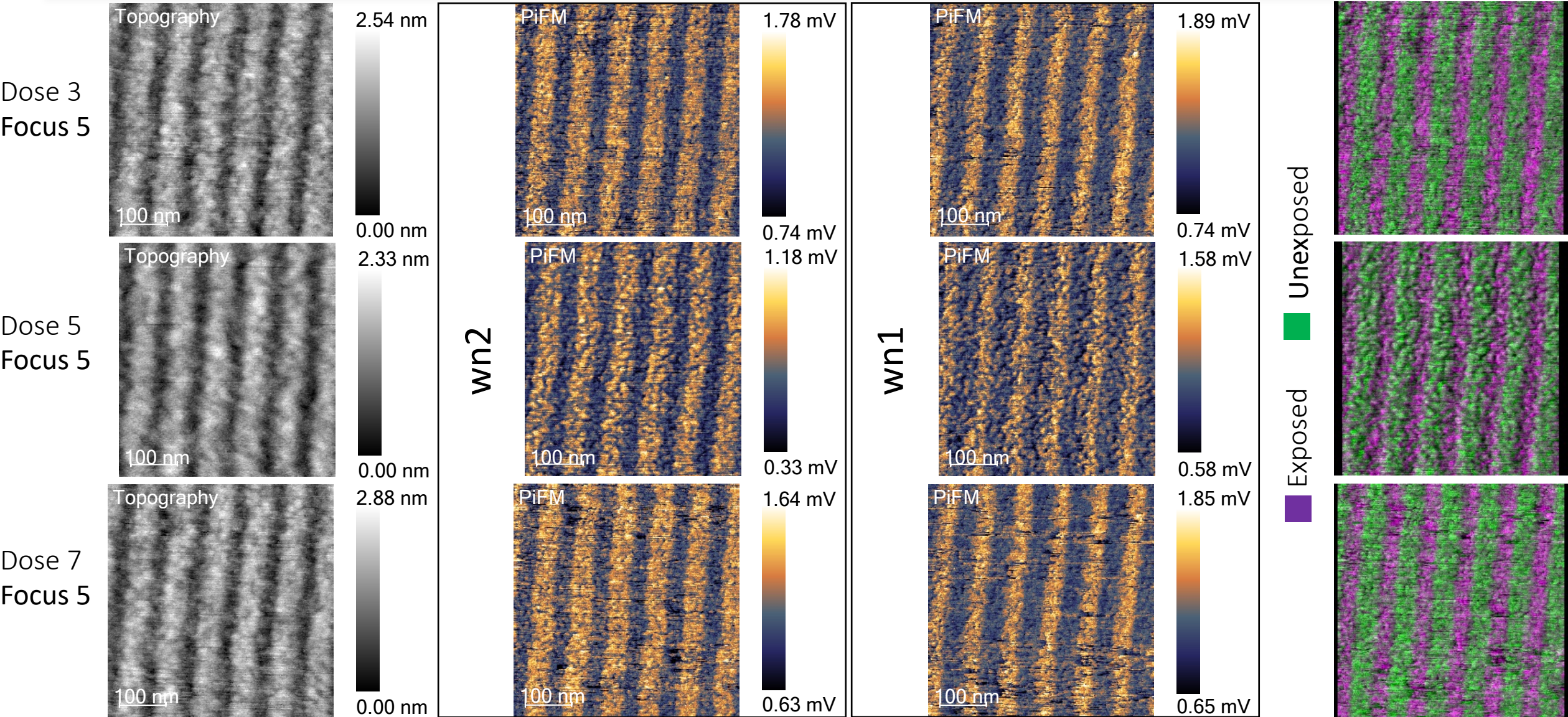
PiFM Signal @ wn1 and wn2 cm^{-1} vs Dose

Clear trends are observed at two wavenumbers. The area average of PiF intensity at wn2 decreases with dose while the area average of PiF intensity at wn1 increases with dose. The signal at wn2 suggest that the chemical change upon exposure seems to stall somewhere between 30 and 50 mJ/cm^2 .

Somewhat similar trend is observed for the rms roughness if one outlier datum is ignored.



Preliminary Results on Patterned MO EUV Resist @ Different Doses



Summary

- IR PiFM measures sample's nanoscale infrared absorption via mechanical force detection.
- It achieves sub-5 nm spatial resolution, single-molecule-level sensitivity, orientation discrimination, and ease-of-use.
- It works equally well with both organic and inorganic materials even at nominal thickness of ~ 1 nm.
- For defect analysis, it complements other existing nanoscale analytical tools, which can only provide elemental information.
- Examples of analyzing surface functionalization/contamination, ultrathin ALD films, and latent chemical images of EUV resists have been shared.
- For accurate identification of defects, it is important that the IR spectra database includes the spectra for all material the sample may be exposed to in its processing steps.



Thank you.

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Thank you.

Samples

- Norway spruce – Tapani Vuorinen, Aalto University, Finland
- Peptoid – Beihang Yu, Lawrence Berkeley Lab, USA
- PCL/AA – Phuong Nguyen-Tri, Université du Québec à Trois-Rivières, Canada
- ODTs on SiO₂ – Stacey Bent, Stanford University, USA
- Various Substrates – Jeff Chinn, IST, USA
- Metal oxide EUV Resist – Patrick Naulleau, Lawrence Berkeley Lab, USA



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